Applied Surface Science 54 (1992) 511–516
North-Holland

Author index

Afonso, C.N., F. Vega, J. Solis, F. Catalina, C. Ortega and J. Siejka, Laser ablation of Ge in an oxygen environment: plasma and film properties 54 (1992) 175
Afonso, C.N., see Ortiz, C. 54 (1992) 201
Afonso, C.N., see Vega, F. 54 (1992) 341
Amato, C.C., J.B. Hudson and L.V. Interrante, Identification of the gas-phase products which occur during the deposition of AlN using the organometallic precursor: $[(CH_3)_2AlNH_2]_3$ 54 (1992) 18
Amirhaghi, S., A. Archer, B. Taguiang, R. McMinn, P. Barnes, S. Tarling and I.W. Boyd, Thin film deposition of dielectric oxides by laser ablation 54 (1992) 205
Archer, A., see Amirhaghi, S. 54 (1992) 205
Armstrong, S.R., M.E. Pemble, A.G. Taylor, B.A. Joyce, J.H. Neave, J. Zhang and D.A. Klug, Laser–surface diagnostics of GaAs growth processes. II. Reflectance anisotropy studies of GaAs growth by MBE 54 (1992) 493
Arthur, G., see Foulon, F. 54 (1992) 291
Auvert, G., see Boughaba, S. 54 (1992) 25

Bachmann, F., see Rieger, D. 54 (1992) 99
Badini, C., M. Bianco, S. Talentino, X.B. Guo and C. Gianoglio, Laser boronizing of some titanium alloys 54 (1992) 374
Baeri, P., L. Torrisi, N. Marino and G. Foti, Ablation of hydroxyapatite by pulsed laser irradiation 54 (1992) 210
Bahners, T., see Kesting, W. 54 (1992) 330
Baier, A., see Hopfe, V. 54 (1992) 78
Baker, J., see Foulon, F. 54 (1992) 291
Barnes, P., see Amirhaghi, S. 54 (1992) 205
Barron, A.R., see Cleaver, W.M. 54 (1992) 8
Bauer, G.H., see Kessler, F. 54 (1992) 430
Beech, F., see Sajjadi, A. 54 (1992) 154
Beech, F., see Naqvi, S.H.H. 54 (1992) 166
Bergonzo, P., P. Patel, I.W. Boyd and U. Kogelschatz, Development of a novel large area excimer lamp for direct photo deposition of thin films 54 (1992) 424
Bertolotti, M., see Craciun, V. 54 (1992) 362
Bertolotti, M., V. Craciun, G. De Cesare, A. Ferrari, A. Jascow, I.N. Mihailescu, G. Mikhailova, A. Cino and M. Rossi, Laser in-diffusion of Ti in $LiNbO_3$ single crystals 54 (1992) 401
Bianco, M., see Badini, C. 54 (1992) 374
Blau, W., see Lemoine, P. 54 (1992) 240
Blondiaux, G., see Boulmer-Leborgne, C. 54 (1992) 349
Boivin, S., see Meunier, M. 54 (1992) 52
Bolle, M. and S. Lazare, Ablation of thin polymer films on Si or metal substrate with the low intensity UV beam of an excimer laser or mercury lamp: advantages of ellipsometric rate measurements 54 (1992) 471
Bostanjoglo, O., see Heinricht, F. 54 (1992) 244
Bostanjoglo, O., W. Marine and P. Thomsen-Schmidt, Laser-induced nucleation of crystals in amorphous Ge films 54 (1992) 302
Boughaba, S. and G. Auvert, Laser-induced deposition of one-micron-size polysilicon lines from mono and trisilane 54 (1992) 25
Boulmer-Leborgne, C., J. Hermann, B. Dubreuil, P. Brault, M.L. DeGiorgi, G. Leggieri, A. Luches, M. Martino, A. Perrone, I.N. Mihailescu, I. Ursu, G. Blondiaux, J.L. Debrun, H. Estrade and B. Rousseau, Direct carbidation of titanium as a result of multipulse UV-laser irradiation of titanium samples in an ambient methane gas 54 (1992) 349
Boyd, I.W., see Sajjadi, A. 54 (1992) 154
Boyd, I.W., see Naqvi, S.H.H. 54 (1992) 166
Boyd, I.W., see Amirhaghi, S. 54 (1992) 205
Boyd, I.W., see Bergonzo, P. 54 (1992) 424
Boyd, I.W., see Kazor, A. 54 (1992) 460
Brands, C., see Krans, R.L. 54 (1992) 117
Brault, P., see Boulmer-Leborgne, C. 54 (1992) 349
Brook, M.R. and G.A. Shafeev, Laser-assisted engraving of HgCdTe under a liquid layer 54 (1992) 336
Buchmann, F., see Schlemm, H. 54 (1992) 298
Buerhop, C., R. Weissmann and N. Lutz, Ablation of silicate glasses by laser

irradiation: modelling and experimental results 54 (1992) 187
Burkhard, H., see Dinges, H.W. 54 (1992) 477

Cabrera, M., see Zouari, I. 54 (1992) 311
Calvo, M., see Zouari, I. 54 (1992) 311
Carlsson, J.O., see Mogyorósi, P. 54 (1992) 46
Catalina, F., see Afonso, C.N. 54 (1992) 175
Caudano, R., see Petit, E.J. 54 (1992) 405
Celis, J.P., M. Franck, J.R. Roos, E.W. Kreutz, A. Gasser, M. Wehner, K. Wissenbach and N. Pattyn, Potential of photon and particle beams for surface treatment of thin ceramic coatings 54 (1992) 322
Chapeaublanc, J.-F., see Petitjean, M. 54 (1992) 453
Cheang, J.C., see Ortiz, C. 54 (1992) 201
Chitica, N., see Craciun, V. 54 (1992) 362
Cino, A., see Bertolotti, M. 54 (1992) 401
Cleaver, W.M., A.R. Barron, Y. Zhang and M. Stuke, Hybrid organometallic compounds of gallium: UV excimer laser photochemistry of Ga(t-C_4H_9)$_n$(CH_3)$_{3-n}$ ($n = 0, 1, 2, 3$) 54 (1992) 8
Conde, O., M.L.G. Ferreira, P. Hochholdinger, A.J. Silvestre and R. Vilar, CO_2 laser induced CVD of TiN 54 (1992) 130
Craciun, D. and V. Craciun, Reactive pulsed laser deposition of TiN 54 (1992) 75
Craciun, D., see Craciun, V. 54 (1992) 362
Craciun, V., see Craciun, D. 54 (1992) 75
Craciun, V., D. Craciun, N. Chitica, I.N. Mihailescu and M. Bertolotti, Laser self-aligned synthesis of $TiSi_2$ 54 (1992) 362
Craciun, V., see Bertolotti, M. 54 (1992) 401
Crean, G.M., see Murtagh, M. 54 (1992) 497
Cros, A., H. Dallaporta, S. Lazare, H. Hiraoka, N. Merk and W. Marine, Properties of Au and Cu layers deposited on photoablated polyphenylquinoxaline surfaces 54 (1992) 278

Dähn, G., see Pauli, M. 54 (1992) 386
Dallaporta, H., see Cros, A. 54 (1992) 278
D'Anna, E., G. Leggieri, A. Luches, M. Martino, A. Perrone, P. Mengucci and I.N. Mihailescu, Multilayer titanium nitride and silicide structures synthesized by multipulse excimer laser irradiation 54 (1992) 353
Debauche, C., C. Licoppe, C. Meriadec, F. Sartoris and J. Flicstein, UV annealing of low temperature photodeposited SiO_2 films with a new powerful lamp source 54 (1992) 435
Debrun, J.L., see Boulmer-Leborgne, C. 54 (1992) 349
De Cesare, G., see Bertolotti, M. 54 (1992) 401
DeGiorgi, M.L., see Boulmer-Leborgne, C. 54 (1992) 349
Delaporte, Ph., see Marine, W. 54 (1992) 264
Desjardins, P., see Meunier, M. 54 (1992) 52
De Unamuno, S., see Elliq, M. 54 (1992) 35
De Unamuno, S., see Mathé, E.L. 54 (1992) 392
Dinges, H.W., H. Burkhard, R. Lösch, H. Nickel and W. Schlapp, Refractive indices of InAlAs and InGaAs/InP from 250 to 1900 nm determined by spectroscopic ellipsometry 54 (1992) 477
Dubreuil, B., see Boulmer-Leborgne, C. 54 (1992) 349
Dyer, P.E., P.H. Key and P. Monk, Ablation studies of Y–Ba–Cu–oxide in oxygen using a pulsed CO_2 laser 54 (1992) 160
Dyer, P.E., S.R. Farrar and P.H. Key, Fast time-response photoacoustic studies and modelling of KrF laser ablated $YBa_2Cu_3O_7$ 54 (1992) 255

Ebert, R., see Reisse, G. 54 (1992) 84
Ebert, T., see Löffler-Peters, A. 54 (1992) 121
Elders, J. and J.D.W. van Voorst, Laser-induced chemical vapor deposition of titanium diboride 54 (1992) 135
Elliq, M., E. Fogarassy, C. Fuchs, J.P. Stoquert, S. de Unamuno, B. Prévot and E.L. Mathé, One-step growth of polycrystalline silicon thin films at low-temperature by ArF excimer laser-induced photo-CVD 54 (1992) 35
Elliq, M., see Mathé, E.L. 54 (1992) 392
Enard, J.P., see Pérez Casero, R. 54 (1992) 147
Erkens, G., see Funken, J. 54 (1992) 141
Esrom, H. and U. Kogelschatz, Metal deposition with a windowless VUV excimer source 54 (1992) 440
Esrom, H., see Zhang, J.-Y. 54 (1992) 465
Esser, A., G. Maidorn and H. Kurz, Photoinduced transient reflectance investigation of process-induced near-surface defects in silicon 54 (1992) 482
Estrade, H., see Boulmer-Leborgne, C. 54 (1992) 349

Farrar, S.R., see Dyer, P.E. 54 (1992) 255
Fernández, D., see González, P. 54 (1992) 108
Fernández, D., P. González, J. Pou, B. León and M. Pérez-Amor, Low-temperature silicon oxide films deposited using a CO_2 laser 54 (1992) 112
Ferrari, A., see Bertolotti, M. 54 (1992) 401
Ferreira, M.L.G., see Conde, O. 54 (1992) 130
Fischer, A., G. Reisse, F. Gänsicke and K. Zimmer, Theoretical and experimental studies of laser-induced chemical vapour deposition of silicon thin films 54 (1992) 41

Flaherty, T., see Murtagh, M. 54 (1992) 497
Flicstein, J., see Debauche, C. 54 (1992) 435
Flint, E.B., J. Messelhäuser and H. Suhr, Laser-induced chemical vapor deposition of rhodium 54 (1992) 56
Flint, E.B., see Messelhäuser, J. 54 (1992) 64
Fogarassy, E., see Elliq, M. 54 (1992) 35
Fogarassy, E., A. Slaoui, C. Fuchs and J.P. Stoquert, Synthesis of SiO_2 thin films by reactive excimer laser ablation 54 (1992) 180
Fogarassy, E., see Mathé, E.L. 54 (1992) 392
Fontaine, B., see Marine, W. 54 (1992) 264
Foresti, M., see Giardini-Guidoni, A. 54 (1992) 171
Forestier, B., see Marine, W. 54 (1992) 264
Fornell, J.-O., see Pietsch, U. 54 (1992) 502
Foti, G., see Baeri, P. 54 (1992) 210
Foulon, F., M. Green, R.A. Lawes, J. Baker, F.N. Goodall and G. Arthur, Laser projection patterned processing of semiconductors 54 (1992) 291
Franck, M., see Celis, J.P. 54 (1992) 322
Fuchs, C., see Elliq, M. 54 (1992) 35
Fuchs, C., see Fogarassy, E. 54 (1992) 180
Fujisaki, Y., Control of the $GaAs/SiO_2$ interface through sulfur passivation and a photo-CVD process 54 (1992) 95
Funken, J., E.W. Kreutz, M. Krösche, H. Sung, A. Voss, G. Erkens, O. Lemmer and T. Leyendecker, Deposition of ceramics by LPVD 54 (1992) 141

Gänsicke, F., see Fischer, A. 54 (1992) 41
Gänsicke, F., see Reisse, G. 54 (1992) 84
Gao, Y., see Lebland, F. 54 (1992) 125
García, E., see González, P. 54 (1992) 108
Gärtner, K., see Weber, B. 54 (1992) 381
Gasser, A., see Celis, J.P. 54 (1992) 322
Geiler, H.-D., see Schlemm, H. 54 (1992) 298
Gerri, M., see Marine, W. 54 (1992) 264
Gianoglio, C., see Badini, C. 54 (1992) 374
Giardini-Guidoni, A., G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo, Production and reactivity of ionic clusters 54 (1992) 171
Golusda, E., R. Lange, K.-D. Lühmann, G. Mollekopf, M. Wacker and H. Stafast, CW CO_2 laser CVD of amorphous hydrogenated silicon (a-Si:H): influence of the deposition geometry 54 (1992) 30
González, P., E. García, J. Pou, D. Fernández, B. León and M. Pérez-Amor, Excimer laser CVD of silicon oxide on GaAs: a comparison with deposition on c-Si 54 (1992) 108
González, P., see Fernández, D. 54 (1992) 112
Goodall, F.N., see Foulon, F. 54 (1992) 291
Green, M., see Foulon, F. 54 (1992) 291
Guo, X.B., see Badini, C. 54 (1992) 374

Heinricht, F. and O. Bostanjoglo, Laser ablation processes imaged by high-speed reflection electron microscopy 54 (1992) 244
Hermann, J., see Boulmer-Leborgne, C. 54 (1992) 349
Hiraoka, H., see Cros, A. 54 (1992) 278
Hochholdinger, P., see Conde, O. 54 (1992) 130
Hopfe, V., A. Tehel, A. Baier and J. Scharsig, IR-laser CVD of TiB_2, TiC_x and TiC_xN_y coatings on carbon fibres 54 (1992) 78
Hudson, J.B., see Amato, C.C. 54 (1992) 18
Hunger, E., H. Pietsch, S. Petzoldt and E. Matthias, Multishot ablation of polymer and metal films at 248 nm 54 (1992) 227

Ihlemann, J., Excimer laser ablation of fused silica 54 (1992) 193
Illmann, U., see Reisse, G. 54 (1992) 84
Inoue, M., see Omori, N. 54 (1992) 232
Interrante, L.V., see Amato, C.C. 54 (1992) 18
Izquierdo, R., see Meunier, M. 54 (1992) 52
Izquierdo, R., see Lecours, A. 54 (1992) 60

Jadin, A., M. Wautelet and L.D. Laude, Excimer laser induced surface modification of thin Ge–Se films 54 (1992) 345
Jascow, A., see Bertolotti, M. 54 (1992) 401
Jeynes, C., see Murtagh, M. 54 (1992) 497
Johansen, H., see Reisse, G. 54 (1992) 84
Joyce, B.A., see Armstrong, S.R. 54 (1992) 493

Kaschner, C., see Weber, B. 54 (1992) 381
Kasko, I., see Weber, B. 54 (1992) 381
Kazor, A. and I.W. Boyd, Low temperature photo-assisted oxidation of silicon 54 (1992) 460
Kerhervé, F., see Pérez Casero, R. 54 (1992) 147
Kessler, F. and G.H. Bauer, VUV excimer light source for deposition of amorphous semiconductors 54 (1992) 430
Kesting, W., D. Knittel, T. Bahners and E. Schollmeyer, Pulse- and time-dependent observation of UV-laser-induced structures on polymer surfaces 54 (1992) 330
Key, P.H., see Dyer, P.E. 54 (1992) 160
Key, P.H., see Dyer, P.E. 54 (1992) 255
Klug, D.A., see Armstrong, S.R. 54 (1992) 493
Knittel, D., see Kesting, W. 54 (1992) 330
Kogelschatz, U., Silent-discharge driven excimer UV sources and their applications 54 (1992) 410
Kogelschatz, U., see Bergonzo, P. 54 (1992) 424
Kogelschatz, U., see Esrom, H. 54 (1992) 440
Kolev, K. and L.D. Laude, CW-laser-induced synthesis of Sb_2Se_3 thin films 54 (1992) 358

Krans, R.L., C. Brands and W.C. Sinke, Kinetics of excimer-laser induced CVD of W 54 (1992) 117
Kreutz, E.W., M. Krösche, H. Sung, A. Voss and K. Wissenbach, Reactive TiN deposition on alloys with laser radiation 54 (1992) 69
Kreutz, E.W., see Funken, J. 54 (1992) 141
Kreutz, E.W., see Celis, J.P. 54 (1992) 322
Krösche, M., see Kreutz, E.W. 54 (1992) 69
Krösche, M., see Funken, J. 54 (1992) 141
Kurpas, P., see Richter, W. 54 (1992) 1
Kurz, H., see Esser, A. 54 (1992) 482

Lange, R., see Golusda, E. 54 (1992) 30
Lapicque, F., see Zouari, I. 54 (1992) 311
Laude, L.D., see Jadin, A. 54 (1992) 345
Laude, L.D., see Kolev, K. 54 (1992) 358
Lavoie, C., see Meunier, M. 54 (1992) 52
Lawes, R.A., see Foulon, F. 54 (1992) 291
Lazare, S., see Cros, A. 54 (1992) 278
Lazare, S., see Bolle, M. 54 (1992) 471
Lebland, F., C. Licoppe, Y. Gao, Y.I. Nissim and S. Rigo, Rapid thermal chemical vapour deposition of SiO_xN_y films 54 (1992) 125
Lecours, A., M. Meunier and R. Izquierdo, Laser-induced damage formation and tungsten deposition on GaAs 54 (1992) 60
Leggieri, G., see Boulmer-Leborgne, C. 54 (1992) 349
Leggieri, G., see D'Anna, E. 54 (1992) 353
Lemmer, O., see Funken, J. 54 (1992) 141
Lemoine, P. and W. Blau, Photoablation of polymers 54 (1992) 240
León, B., see González, P. 54 (1992) 108
León, B., see Fernández, D. 54 (1992) 112
Leyendecker, T., see Funken, J. 54 (1992) 141
Licoppe, C., see Lebland, F. 54 (1992) 125
Licoppe, C., see Debauche, C. 54 (1992) 435
Licoppe, C., C. Meriadec, Y.I. Nissim and J.M. Moison, Surface mechanisms in the UVCVD of SiO_2 films 54 (1992) 445
Löffler-Peters, A., J. Müller and T. Ebert, Deposition of SiON by ArF laser CVD 54 (1992) 121
Lösch, R., see Dinges, H.W. 54 (1992) 477
Luches, A., see Boulmer-Leborgne, C. 54 (1992) 349
Luches, A., see D'Anna, E. 54 (1992) 353
Lühmann, K.-D., see Golusda, E. 54 (1992) 30
Lutz, N., see Buerhop, C. 54 (1992) 187

Mai, H. and W. Pompe, Manufacture and characterization of soft X-ray mirrors by laser ablation 54 (1992) 215
Maidorn, G., see Esser, A. 54 (1992) 482
Marine, W., M. Gerri, J.M. Scotto d'Aniello, M. Sentis, Ph. Delaporte, B. Forestier and B. Fontaine, Analysis of the plasma expansion dynamics by optical time-of-flight measurements 54 (1992) 264
Marine, W., see Cros, A. 54 (1992) 278
Marine, W., see Bostanjoglo, O. 54 (1992) 302
Marino, N., see Baeri, P. 54 (1992) 210
Martino, M., see Boulmer-Leborgne, C. 54 (1992) 349
Martino, M., see D'Anna, E. 54 (1992) 353
Mathé, E.L., see Elliq, M. 54 (1992) 35
Mathé, E.L., A. Naudon, M. Elliq, E. Fogarassy and S. de Unamuno, Influence of hydrogen on the structure and surface morphology of pulsed ArF excimer laser crystallized amorphous silicon thin films 54 (1992) 392
Matthias, E., see Hunger, E. 54 (1992) 227
McMinn, R., see Amirhaghi, S. 54 (1992) 205
Mengucci, P., see D'Anna, E. 54 (1992) 353
Meriadec, C., see Debauche, C. 54 (1992) 435
Meriadec, C., see Licoppe, C. 54 (1992) 445
Merk, N., see Cros, A. 54 (1992) 278
Messelhäuser, J., see Flint, E.B. 54 (1992) 56
Messelhäuser, J., E.B. Flint and H. Suhr, Laser induced CVD of gold using new precursors 54 (1992) 64
Metzger, H., see Pietsch, U. 54 (1992) 502
Metzger, H., see Rugel, S. 54 (1992) 507
Meunier, M., C. Lavoie, S. Boivin, R. Izquierdo and P. Desjardins, Modeling KrF excimer laser induced deposition of titanium from titanium tetrachloride 54 (1992) 52
Meunier, M., see Lecours, A. 54 (1992) 60
Mihailescu, I.N., see Boulmer-Leborgne, C. 54 (1992) 349
Mihailescu, I.N., see D'Anna, E. 54 (1992) 353
Mihailescu, I.N., see Craciun, V. 54 (1992) 362
Mihailescu, I.N., see Bertolotti, M. 54 (1992) 401
Mikhailova, G., see Bertolotti, M. 54 (1992) 401
Mogyorósi, P., J.O. Carlsson and M. Moradi, Spectroscopic investigations of gas-phase chemistry during laser-induced photolytic CVD of W 54 (1992) 46
Moison, J.M., see Licoppe, C. 54 (1992) 445
Mollekopf, G., see Golusda, E. 54 (1992) 30
Monk, P., see Dyer, P.E. 54 (1992) 160
Moradi, M., see Mogyorósi, P. 54 (1992) 46
Müller, J., see Löffler-Peters, A. 54 (1992) 121
Müller, J., see Pauli, M. 54 (1992) 386
Murtagh, M., G.M. Crean, T. Flaherty and C. Jeynes, Sensitivity of a modulated optical reflectance probe to process-induced lattice disorder 54 (1992) 497

Naqvi, S.H.H., F. Beech and I.W. Boyd, In-situ and multilayer laser ablation deposition of $Pb_2Sr_2Y_{0.5}Ca_{0.5}Cu_3O_{8+\delta}$ thin films 54 (1992) 166

Naudon, A., see Mathé, E.L. 54 (1992) 392
Neave, J.H., see Armstrong, S.R. 54 (1992) 493
Nickel, H., see Dinges, H.W. 54 (1992) 477
Nishiyama, I., see Uesugi, F. 54 (1992) 284
Nissim, Y.I., see Lebland, F. 54 (1992) 125
Nissim, Y.I., see Licoppe, C. 54 (1992) 445

Omori, N. and M. Inoue, Excimer laser ablation of inorganic materials 54 (1992) 232
Ortega, C., see Afonso, C.N. 54 (1992) 175
Ortega, C., see Ortiz, C. 54 (1992) 201
Ortiz, C., C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka, Laser deposition of copper oxide thin films: contrast with sputtering 54 (1992) 201
Ortiz, C., see Vega, F. 54 (1992) 341

Patel, P., see Bergonzo, P. 54 (1992) 424
Pattyn, N., see Celis, J.P. 54 (1992) 322
Pauli, M., G. Dähn and J. Müller, Comparison of laser and line-electron beam recrystallization of thin polycrystalline silicon films 54 (1992) 386
Peisl, J., see Pietsch, U. 54 (1992) 502
Peisl, J., see Rugel, S. 54 (1992) 507
Pemble, M.E., A. Stafford and A.G. Taylor, Laser–surface diagnostics of GaAs growth processes. I. The influence of surface contamination upon optical second harmonic generation from GaAs (100) surfaces 54 (1992) 490
Pemble, M.E., see Armstrong, S.R. 54 (1992) 493
Pérez-Amor, M., see González, P. 54 (1992) 108
Pérez-Amor, M., see Fernández, D. 54 (1992) 112
Pérez Casero, R., F. Kerhervé, J.P. Enard, J. Perrière and P. Regnier, Study of laser ablation of BiSrCaCuO 54 (1992) 147
Perrière, J., see Pérez Casero, R. 54 (1992) 147
Perrin, J., see Petitjean, M. 54 (1992) 453
Perrone, A., see Boulmer-Leborgne, C. 54 (1992) 349
Perrone, A., see D'Anna, E. 54 (1992) 353
Petit, E.J. and R. Caudano, Chemical reactions at metallic and metal/semiconductor interfaces stimulated by pulsed laser annealing 54 (1992) 405
Petitjean, M., N. Proust, J.-F. Chapeaublanc and J. Perrin, Improvement of the SiO_2 deposition by 185 nm photolysis of N_2O and SiH_4 by addition of neopentane 54 (1992) 453
Petzoldt, S., see Hunger, E. 54 (1992) 227
Piccirillo, S., see Giardini-Guidoni, A. 54 (1992) 171
Pietsch, H., see Hunger, E. 54 (1992) 227
Pietsch, U., W. Seifert, J.-O. Fornell, H. Rhan, H. Metzger, S. Rugel and J. Peisl, Investigation of a semiconductor superlattice by use of grazing incidence X-ray diffraction 54 (1992) 502
Pizzella, G., see Giardini-Guidoni, A. 54 (1992) 171
Pompe, W., see Mai, H. 54 (1992) 215
Pou, J., see González, P. 54 (1992) 108
Pou, J., see Fernández, D. 54 (1992) 112
Preuss, S. and M. Stuke, Suitable precursor/solvent systems for laser-induced surface prenucleation 54 (1992) 308
Prévot, B., see Elliq, M. 54 (1992) 35
Proust, N., see Petitjean, M. 54 (1992) 453

Regnier, P., see Pérez Casero, R. 54 (1992) 147
Reisse, G., see Fischer, A. 54 (1992) 41
Reisse, G., F. Gaensicke, R. Ebert, U. Illmann and H. Johansen, Laser-induced chemical vapour deposition of conductive and insulating thin films 54 (1992) 84
Reisse, G., see Weissmantel, S. 54 (1992) 317
Rhan, H., see Pietsch, U. 54 (1992) 502
Richter, W., P. Kurpas and M. Waschbüsch, Photodecomposition of precursors for metal organic vapour phase epitaxy 54 (1992) 1
Rieger, D. and F. Bachmann, ArF laser induced CVD of SiO_2 films: a search for the best suitable precursors 54 (1992) 99
Rigo, S., see Lebland, F. 54 (1992) 125
Roos, J.R., see Celis, J.P. 54 (1992) 322
Rossi, M., see Bertolotti, M. 54 (1992) 401
Rousseau, B., see Boulmer-Leborgne, C. 54 (1992) 349
Rugel, S., see Pietsch, U. 54 (1992) 502
Rugel, S., H. Metzger, G. Wallner and J. Peisl, Grazing incidence X-ray diffraction on silicon after ion implantation and thermal annealing 54 (1992) 507

Saba, F., see Sajjadi, A. 54 (1992) 154
Sajjadi, A., M.K. Yau, F. Saba, F. Beech and I.W. Boyd, Laser ablation deposition of PbO/BiPbSrCaCuO 54 (1992) 154
Sartoris, F., see Debauche, C. 54 (1992) 435
Scharsig, J., see Hopfe, V. 54 (1992) 78
Schlapp, W., see Dinges, H.W. 54 (1992) 477
Schlemm, H., F. Buchmann and H.-D. Geiler, Laser desorption on Si surfaces by use of multiple excimer laser pulses 54 (1992) 298
Schollmeyer, E., see Kesting, W. 54 (1992) 330
Schulze, S., see Weissmantel, S. 54 (1992) 317
Scotto d'Aniello, J.M., see Marine, W. 54 (1992) 264
Seifert, W., see Pietsch, U. 54 (1992) 502
Sentis, M., see Marine, W. 54 (1992) 264
Serna, R., see Vega, F. 54 (1992) 341
Shafeev, G.A., see Brook, M.R. 54 (1992) 336
Siejka, J., see Afonso, C.N. 54 (1992) 175
Siejka, J., see Ortiz, C. 54 (1992) 201
Silverans, R.E., see Wuyts, K. 54 (1992) 366
Silvestre, A.J., see Conde, O. 54 (1992) 130

Sinke, W.C., see Krans, R.L. 54 (1992) 117
Slaoui, A., see Fogarassy, E. 54 (1992) 180
Snels, M., see Giardini-Guidoni, A. 54 (1992) 171
Solis, J., see Afonso, C.N. 54 (1992) 175
Solis, J., see Ortiz, C. 54 (1992) 201
Solis, J., see Vega, F. 54 (1992) 341
Späth, M. and M. Stuke, Laser ablation of dyes 54 (1992) 237
Stafast, H., see Golusda, E. 54 (1992) 30
Stafford, A., see Pemble, M.E. 54 (1992) 490
Stoquert, J.P., see Elliq, M. 54 (1992) 35
Stoquert, J.P., see Fogarassy, E. 54 (1992) 180
Stuke, M., see Cleaver, W.M. 54 (1992) 8
Stuke, M., see Späth, M. 54 (1992) 237
Stuke, M., see Preuss, S. 54 (1992) 308
Suhr, H., see Flint, E.B. 54 (1992) 56
Suhr, H., see Messelhäuser, J. 54 (1992) 64
Sung, H., see Kreutz, E.W. 54 (1992) 69
Sung, H., see Funken, J. 54 (1992) 141

Taguiang, B., see Amirhaghi, S. 54 (1992) 205
Talentino, S., see Badini, C. 54 (1992) 374
Tarling, S., see Amirhaghi, S. 54 (1992) 205
Taylor, A.G., see Pemble, M.E. 54 (1992) 490
Taylor, A.G., see Armstrong, S.R. 54 (1992) 493
Teghil, R., see Giardini-Guidoni, A. 54 (1992) 171
Tehel, A., see Hopfe, V. 54 (1992) 78
Thomsen-Schmidt, P., see Bostanjoglo, O. 54 (1992) 302
Torrisi, L., see Baeri, P. 54 (1992) 210

Uesugi, F. and I. Nishiyama, Resistless inverse projection patterning of aluminum by using synchrotron radiation induced suppression of thermal chemical vapor deposition 54 (1992) 284
Ursu, I., see Boulmer-Leborgne, C. 54 (1992) 349

Van Voorst, J.D.W., see Elders, J. 54 (1992) 135
Vega, F., see Afonso, C.N. 54 (1992) 175
Vega, F., see Ortiz, C. 54 (1992) 201
Vega, F., C.N. Afonso, J. Solis, R. Serna and C. Ortiz, UV-laser-induced oxidation kinetics of c-Ge: transient reflectivity study 54 (1992) 341
Vilar, R., see Conde, O. 54 (1992) 130
Voss, A., see Kreutz, E.W. 54 (1992) 69
Voss, A., see Funken, J. 54 (1992) 141

Wacker, M., see Golusda, E. 54 (1992) 30
Wallner, G., see Rugel, S. 54 (1992) 507
Waschbüsch, M., see Richter, W. 54 (1992) 1
Watté, J., see Wuyts, K. 54 (1992) 366
Wautelet, M., see Jadin, A. 54 (1992) 345
Weber, B., K. Gärtner, A. Witzmann, C. Kaschner and I. Kasko, Non-equilibrium epitaxial silicides – a special effect of silicide formation by ns-laser irradiation 54 (1992) 381
Wehner, M., see Celis, J.P. 54 (1992) 322
Weissmann, R., see Buerhop, C. 54 (1992) 187
Weissmantel, S., G. Reisse and S. Schulze, Laser-induced structural phase changes in i-carbon films 54 (1992) 317
Wiesendanger, R., Fabrication of nanometer structures using STM 54 (1992) 271
Willwohl, H. and J. Wolfrum, Excimer laser photolysis of metalorganic complexes of platinum and palladium in the gas phase 54 (1992) 89
Wissenbach, K., see Kreutz, E.W. 54 (1992) 69
Wissenbach, K., see Celis, J.P. 54 (1992) 322
Witzmann, A., see Weber, B. 54 (1992) 381
Wolfrum, J., see Willwohl, H. 54 (1992) 89
Wuyts, K., J. Watté and R.E. Silverans, Intriguing properties of pulsed laser beam mixed Au/Te/Au/GaAs ohmic contacts 54 (1992) 366

Yau, M.K., see Sajjadi, A. 54 (1992) 154

Zhang, J., see Armstrong, S.R. 54 (1992) 493
Zhang, J.-Y. and H. Esrom, UV-induced decomposition of adsorbed Cu-acetylacetonate films at room temperature for electroless metal plating 54 (1992) 465
Zhang, Y., see Cleaver, W.M. 54 (1992) 8
Zimmer, K., see Fischer, A. 54 (1992) 41
Zouari, I., M. Calvo, F. Lapicque and M. Cabrera, Influence of laser assistance on the nucleation and growth processes occurring during the electrodeposition of zinc 54 (1992) 311

Applied Surface Science 54 (1992) 517–535
North-Holland

Subject index

Ablation

Deposition of ceramics by LPVD, J. Funken, E.W. Kreutz, M. Krösche, H. Sung, A. Voss, G. Erkens, O. Lemmer and T. Leyendecker 54 (1992) 141
Study of laser ablation of BiSrCaCuO, R. Pérez Casero, F. Kerhervé, J.P. Enard, J. Perrière and P. Regnier 54 (1992) 147
Laser ablation deposition of PbO/Bi-PbSrCaCuO, A. Sajjadi, M.K. Yau, F. Saba, F. Beech and I.W. Boyd 54 (1992) 154
Ablation studies of Y–Ba–Cu–oxide in oxygen using a pulsed CO_2 laser, P.E. Dyer, P.H. Key and P. Monk 54 (1992) 160
In-situ and multilayer laser ablation deposition of $Pb_2Sr_2Y_{0.5}Ca_{0.5}Cu_3O_{8+\delta}$ thin films, S.H.H. Naqvi, F. Beech and I.W. Boyd 54 (1992) 166
Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171
Laser ablation of Ge in an oxygen environment: plasma and film properties, C.N. Afonso, F. Vega, J. Solis, F. Catalina, C. Ortega and J. Siejka 54 (1992) 175
Synthesis of SiO_2 thin films by reactive excimer laser ablation, E. Fogarassy, A. Slaoui, C. Fuchs and J.P. Stoquert 54 (1992) 180
Ablation of silicate glasses by laser irradiation: modelling and experimental results, C. Buerhop, R. Weissmann and N. Lutz 54 (1992) 187
Excimer laser ablation of fused silica, J. Ihlemann 54 (1992) 193
Laser deposition of copper oxide thin films: contrast with sputtering, C. Ortiz, C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka 54 (1992) 201
Thin film deposition of dielectric oxides by laser ablation, S. Amirhaghi, A. Archer, B. Taguiang, R. McMinn, P. Barnes, S. Tarling and I.W. Boyd 54 (1992) 205
Ablation of hydroxyapatite by pulsed laser irradiation, P. Baeri, L. Torrisi, N. Marino and G. Foti 54 (1992) 210
Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215
Multishot ablation of polymer and metal films at 248 nm, E. Hunger, H. Pietsch, S. Petzoldt and E. Matthias 54 (1992) 227
Excimer laser ablation of inorganic materials, N. Omori and M. Inoue 54 (1992) 232
Laser ablation of dyes, M. Späth and M. Stuke 54 (1992) 237
Photoablation of polymers, P. Lemoine and W. Blau 54 (1992) 240
Laser ablation processes imaged by high-speed reflection electron microscopy, F. Heinricht and O. Bostanjoglo 54 (1992) 244
Fast time-response photoacoustic studies and modelling of KrF laser ablated $YBa_2Cu_3O_7$, P.E. Dyer, S.R. Farrar and P.H. Key 54 (1992) 255
Analysis of the plasma expansion dynamics by optical time-of-flight measurements, W. Marine, M. Gerri, J.M. Scotto d'Aniello, M. Sentis, Ph. Delaporte, B. Forestier and B. Fontaine 54 (1992) 264
Properties of Au and Cu layers deposited on photoablated polyphenylquinoxaline surfaces, A. Cros, H. Dallaporta, S. Lazare, H. Hiraoka, N. Merk and W. Marine 54 (1992) 278
Ablation of thin polymer films on Si or metal substrate with the low intensity UV beam of an excimer laser or mercury lamp: advantages of ellipsometric rate measurements, M. Bolle and S. Lazare 54 (1992) 471

Alloys

Laser boronizing of some titanium alloys, C. Badini, M. Bianco, S. Talentino, X.B. Guo and C. Gianoglio 54 (1992) 374

Aluminium

Multishot ablation of polymer and metal films at 248 nm, E. Hunger, H. Pietsch, S. Petzoldt and E. Matthias 54 (1992) 227

Resistless inverse projection patterning of aluminum by using synchrotron radiation induced suppression of thermal chemical vapor deposition, F. Uesugi and I. Nishiyama 54 (1992) 284
Chemical reactions at metallic and metal/semiconductor interfaces stimulated by pulsed laser annealing, E.J. Petit and R. Caudano 54 (1992) 405

Amorphous materials

CW CO_2 laser CVD of amorphous hydrogenated silicon (a-Si:H): influence of the deposition geometry, E. Golusda, R. Lange, K.-D. Lühmann, G. Mollekopf, M. Wacker and H. Stafast 54 (1992) 30
Laser-induced nucleation of crystals in amorphous Ge films, O. Bostanjoglo, W. Marine and P. Thomsen-Schmidt 54 (1992) 302
VUV excimer light source for deposition of amorphous semiconductors, F. Kessler and G.H. Bauer 54 (1992) 430

Antimony

CW-laser-induced synthesis of Sb_2Se_3 thin films, K. Kolev and L.D. Laude 54 (1992) 358
Chemical reactions at metallic and metal/semiconductor interfaces stimulated by pulsed laser annealing, E.J. Petit and R. Caudano 54 (1992) 405

Arsenic

Photodecomposition of precursors for metal organic vapour phase epitaxy, W. Richter, P. Kurpas and M. Waschbüsch 54 (1992) 1

Auger electron spectroscopy

Laser-induced damage formation and tungsten deposition on GaAs, A. Lecours, M. Meunier and R. Izquierdo 54 (1992) 60
Ablation of hydroxyapatite by pulsed laser irradiation, P. Baeri, L. Torrisi, N. Marino and G. Foti 54 (1992) 210
Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215
Excimer laser ablation of inorganic materials, N. Omori and M. Inoue 54 (1992) 232
Resistless inverse projection patterning of aluminum by using synchrotron radiation induced suppression of thermal chemical vapor deposition, F. Uesugi and I. Nishiyama 54 (1992) 284
Laser desorption on Si surfaces by use of multiple excimer laser pulses, H. Schlemm, F. Buchmann and H.-D. Geiler 54 (1992) 298
Excimer laser induced surface modification of thin Ge–Se films, A. Jadin, M. Wautelet and L.D. Laude 54 (1992) 345
Laser self-aligned synthesis of $TiSi_2$, V. Craciun, D. Craciun, N. Chitica, I.N. Mihailescu and M. Bertolotti 54 (1992) 362
Chemical reactions at metallic and metal/semiconductor interfaces stimulated by pulsed laser annealing, E.J. Petit and R. Caudano 54 (1992) 405

Borides

IR-laser CVD of TiB_2, TiC_x and TiC_xN_y coatings on carbon fibres, V. Hopfe, A. Tehel, A. Baier and J. Scharsig 54 (1992) 78
Laser-induced chemical vapor deposition of titanium diboride, J. Elders and J.D.W. van Voorst 54 (1992) 135
Laser boronizing of some titanium alloys, C. Badini, M. Bianco, S. Talentino, X.B. Guo and C. Gianoglio 54 (1992) 374

Cadmium telluride

Laser-assisted engraving of HgCdTe under a liquid layer, M.R. Brook and G.A. Shafeev 54 (1992) 336

Carbon

Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215
Laser desorption on Si surfaces by use of multiple excimer laser pulses, H. Schlemm, F. Buchmann and H.-D. Geiler 54 (1992) 298
Laser-induced structural phase changes in i-carbon films, S. Weissmantel, G. Reisse and S. Schulze 54 (1992) 317

Ceramics

Deposition of ceramics by LPVD, J. Funken, E.W. Kreutz, M. Krösche, H.

Sung, A. Voss, G. Erkens, O. Lemmer and T. Leyendecker 54 (1992) 141
Ablation of hydroxyapatite by pulsed laser irradiation, P. Baeri, L. Torrisi, N. Marino and G. Foti 54 (1992) 210
Potential of photon and particle beams for surface treatment of thin ceramic coatings, J.P. Celis, M. Franck, J.R. Roos, E.W. Kreutz, A. Gasser, M. Wehner, K. Wissenbach and N. Pattyn 54 (1992) 322

Chemical vapour deposition

Photodecomposition of precursors for metal organic vapour phase epitaxy, W. Richter, P. Kurpas and M. Waschbüsch 54 (1992) 1
Hybrid organometallic compounds of gallium: UV excimer laser photochemistry of $Ga(t\text{-}C_4H_9)_n(CH_3)_{3-n}$ (n = 0, 1, 2, 3), W.M. Cleaver, A.R. Barron, Y. Zhang and M. Stuke 54 (1992) 8
Identification of the gas-phase products which occur during the deposition of AlN using the organometallic precursor: $[(CH_3)_2AlNH_2]_3$, C.C. Amato, J.B. Hudson and L.V. Interrante 54 (1992) 18
Laser-induced deposition of one-micron-size polysilicon lines from mono and trisilane, S. Boughaba and G. Auvert 54 (1992) 25
CW CO_2 laser CVD of amorphous hydrogenated silicon (a-Si:H): influence of the deposition geometry, E. Golusda, R. Lange, K.-D. Lühmann, G. Mollekopf, M. Wacker and H. Stafast 54 (1992) 30
One-step growth of polycrystalline silicon thin films at low-temperature by ArF excimer laser-induced photo-CVD, M. Elliq, E. Fogarassy, C. Fuchs, J.P. Stoquert, S. de Unamuno, B. Prévot and E.L. Mathé 54 (1992) 35
Theoretical and experimental studies of laser-induced chemical vapour deposition of silicon thin films, A. Fischer, G. Reisse, F. Gänsicke and K. Zimmer 54 (1992) 41
Spectroscopic investigations of gas-phase chemistry during laser-induced photolytic CVD of W, P. Mogyorósi, J.O. Carlsson and M. Moradi 54 (1992) 46
Modeling KrF excimer laser induced deposition of titanium from titanium tetrachloride, M. Meunier, C. Lavoie, S. Boivin, R. Izquierdo and P. Desjardins 54 (1992) 52
Laser-induced chemical vapor deposition of rhodium, E.B. Flint, J. Messelhäuser and H. Suhr 54 (1992) 56
Laser-induced damage formation and tungsten deposition on GaAs, A. Lecours, M. Meunier and R. Izquierdo 54 (1992) 60
Laser induced CVD of gold using new precursors, J. Messelhäuser, E.B. Flint and H. Suhr 54 (1992) 64
Reactive TiN deposition on alloys with laser radiation, E.W. Kreutz, M. Krösche, H. Sung, A. Voss and K. Wissenbach 54 (1992) 69
Reactive pulsed laser deposition of TiN, D. Craciun and V. Craciun 54 (1992) 75
IR-laser CVD of TiB_2, TiC_x and TiC_xN_y coatings on carbon fibres, V. Hopfe, A. Tehel, A. Baier and J. Scharsig 54 (1992) 78
Laser-induced chemical vapour deposition of conductive and insulating thin films, G. Reisse, F. Gaensicke, R. Ebert, U. Illmann and H. Johansen 54 (1992) 84
Excimer laser photolysis of metalorganic complexes of platinum and palladium in the gas phase, H. Willwohl and J. Wolfrum 54 (1992) 89
Control of the $GaAs/SiO_2$ interface through sulfur passivation and a photo-CVD process, Y. Fujisaki 54 (1992) 95
ArF laser induced CVD of SiO_2 films: a search for the best suitable precursors, D. Rieger and F. Bachmann 54 (1992) 99
Excimer laser CVD of silicon oxide on GaAs: a comparison with deposition on c-Si, P. González, E. García, J. Pou, D. Fernández, B. León and M. Pérez-Amor 54 (1992) 108
Low-temperature silicon oxide films deposited using a CO_2 laser, D. Fernández, P. González, J. Pou, B. León and M. Pérez-Amor 54 (1992) 112
Kinetics of excimer-laser induced CVD of W, R.L. Krans, C. Brands and W.C. Sinke 54 (1992) 117
Deposition of SiON by ArF laser CVD, A. Löffler-Peters, J. Müller and T. Ebert 54 (1992) 121
Rapid thermal chemical vapour deposition of SiO_xN_y films, F. Lebland, C. Licoppe, Y. Gao, Y.I. Nissim and S. Rigo 54 (1992) 125
CO_2 laser induced CVD of TiN, O. Conde, M.L.G. Ferreira, P. Hochholdinger, A.J. Silvestre and R. Vilar 54 (1992) 130
Laser-induced chemical vapor deposition

of titanium diboride, J. Elders and J.D.W. van Voorst 54 (1992) 135
Deposition of ceramics by LPVD, J. Funken, E.W. Kreutz, M. Krösche, H. Sung, A. Voss, G. Erkens, O. Lemmer and T. Leyendecker 54 (1992) 141
Resistless inverse projection patterning of aluminum by using synchrotron radiation induced suppression of thermal chemical vapor deposition, F. Uesugi and I. Nishiyama 54 (1992) 284
VUV excimer light source for deposition of amorphous semiconductors, F. Kessler and G.H. Bauer 54 (1992) 430
UV annealing of low temperature photodeposited SiO_2 films with a new powerful lamp source, C. Debauche, C. Licoppe, C. Meriadec, F. Sartoris and J. Flicstein 54 (1992) 435
Surface mechanisms in the UVCVD of SiO_2 films, C. Licoppe, C. Meriadec, Y.I. Nissim and J.M. Moison 54 (1992) 445
Improvement of the SiO_2 deposition by 185 nm photolysis of N_2O and SiH_4 by addition of neopentane, M. Petitjean, N. Proust, J.-F. Chapeaublanc and J. Perrin 54 (1992) 453

Chromium

Multishot ablation of polymer and metal films at 248 nm, E. Hunger, H. Pietsch, S. Petzoldt and E. Matthias 54 (1992) 227

Cobalt

Laser-induced chemical vapour deposition of conductive and insulating thin films, G. Reisse, F. Gaensicke, R. Ebert, U. Illmann and H. Johansen 54 (1992) 84

Compound formation

Reactive TiN deposition on alloys with laser radiation, E.W. Kreutz, M. Krösche, H. Sung, A. Voss and K. Wissenbach 54 (1992) 69
Excimer laser induced surface modification of thin Ge–Se films, A. Jadin, M. Wautelet and L.D. Laude 54 (1992) 345
CW-laser-induced synthesis of Sb_2Se_3 thin films, K. Kolev and L.D. Laude 54 (1992) 358
Laser self-aligned synthesis of $TiSi_2$, V. Craciun, D. Craciun, N. Chitica, I.N. Mihailescu and M. Bertolotti 54 (1992) 362
Non-equilibrium epitaxial silicides – a special effect of silicide formation by ns-laser irradiation, B. Weber, K. Gärtner, A. Witzmann, C. Kaschner and I. Kasko 54 (1992) 381
Chemical reactions at metallic and metal/semiconductor interfaces stimulated by pulsed laser annealing, E.J. Petit and R. Caudano 54 (1992) 405

Copper

Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171
Laser deposition of copper oxide thin films: contrast with sputtering, C. Ortiz, C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka 54 (1992) 201
Multishot ablation of polymer and metal films at 248 nm, E. Hunger, H. Pietsch, S. Petzoldt and E. Matthias 54 (1992) 227
Properties of Au and Cu layers deposited on photoablated polyphenylquinoxaline surfaces, A. Cros, H. Dallaporta, S. Lazare, H. Hiraoka, N. Merk and W. Marine 54 (1992) 278
Suitable precursor/solvent systems for laser-induced surface prenucleation, S. Preuss and M. Stuke 54 (1992) 308
Silent-discharge driven excimer UV sources and their applications, U. Kogelschatz 54 (1992) 410
UV-induced decomposition of adsorbed Cu-acetylacetonate films at room temperature for electroless metal plating, J.-Y. Zhang and H. Esrom 54 (1992) 465

Crystallization

Laser-induced nucleation of crystals in amorphous Ge films, O. Bostanjoglo, W. Marine and P. Thomsen-Schmidt 54 (1992) 302
Laser-induced structural phase changes in i-carbon films, S. Weissmantel, G. Reisse and S. Schulze 54 (1992) 317
Comparison of laser and line-electron beam recrystallization of thin polycrystalline silicon films, M. Pauli, G. Dähn and J. Müller 54 (1992) 386
Influence of hydrogen on the structure and surface morphology of pulsed ArF excimer laser crystallized amorphous silicon thin films, E.L. Mathé, A. Naudon, M. Elliq, E. Fogarassy and S. de Unamuno 54 (1992) 392

Grazing incidence X-ray diffraction on silicon after ion implantation and thermal annealing, S. Rugel, H. Metzger, G. Wallner and J. Peisl 54 (1992) 507

Cuprous oxide

Laser deposition of copper oxide thin films: contrast with sputtering, C. Ortiz, C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka 54 (1992) 201

Diffusion

Laser in-diffusion of Ti in $LiNbO_3$ single crystals, M. Bertolotti, V. Craciun, G. De Cesare, A. Ferrari, A. Jascow, I.N. Mihailescu, G. Mikhailova, A. Cino and M. Rossi 54 (1992) 401

Electrical properties

Laser-induced chemical vapor deposition of rhodium, E.B. Flint, J. Messelhäuser and H. Suhr 54 (1992) 56

Control of the $GaAs/SiO_2$ interface through sulfur passivation and a photo-CVD process, Y. Fujisaki 54 (1992) 95

In-situ and multilayer laser ablation deposition of $Pb_2Sr_2Y_{0.5}Ca_{0.5}Cu_3O_{8+\delta}$ thin films, S.H.H. Naqvi, F. Beech and I.W. Boyd 54 (1992) 166

Intriguing properties of pulsed laser beam mixed Au/Te/Au/GaAs ohmic contacts, K. Wuyts, J. Watté and R.E. Silverans 54 (1992) 366

UV annealing of low temperature photodeposited SiO_2 films with a new powerful lamp source, C. Debauche, C. Licoppe, C. Meriadec, F. Sartoris and J. Flicstein 54 (1992) 435

Electron diffraction

Laser-induced structural phase changes in i-carbon films, S. Weissmantel, G. Reisse and S. Schulze 54 (1992) 317

Electron microscopy

Laser-induced deposition of one-micron-size polysilicon lines from mono and trisilane, S. Boughaba and G. Auvert 54 (1992) 25

One-step growth of polycrystalline silicon thin films at low-temperature by ArF excimer laser-induced photo-CVD, M. Elliq, E. Fogarassy, C. Fuchs, J.P. Stoquert, S. de Unamuno, B. Prévot and E.L. Mathé 54 (1992) 35

Laser-induced damage formation and tungsten deposition on GaAs, A. Lecours, M. Meunier and R. Izquierdo 54 (1992) 60

Reactive TiN deposition on alloys with laser radiation, E.W. Kreutz, M. Krösche, H. Sung, A. Voss and K. Wissenbach 54 (1992) 69

IR-laser CVD of TiB_2, TiC_x and TiC_xN_y coatings on carbon fibres, V. Hopfe, A. Tehel, A. Baier and J. Scharsig 54 (1992) 78

Laser-induced chemical vapour deposition of conductive and insulating thin films, G. Reisse, F. Gaensicke, R. Ebert, U. Illmann and H. Johansen 54 (1992) 84

ArF laser induced CVD of SiO_2 films: a search for the best suitable precursors, D. Rieger and F. Bachmann 54 (1992) 99

CO_2 laser induced CVD of TiN, O. Conde, M.L.G. Ferreira, P. Hochholdinger, A.J. Silvestre and R. Vilar 54 (1992) 130

Laser-induced chemical vapor deposition of titanium diboride, J. Elders and J.D.W. van Voorst 54 (1992) 135

Deposition of ceramics by LPVD, J. Funken, E.W. Kreutz, M. Krösche, H. Sung, A. Voss, G. Erkens, O. Lemmer and T. Leyendecker 54 (1992) 141

Ablation studies of Y–Ba–Cu–oxide in oxygen using a pulsed CO_2 laser, P.E. Dyer, P.H. Key and P. Monk 54 (1992) 160

In-situ and multilayer laser ablation deposition of $Pb_2Sr_2Y_{0.5}Ca_{0.5}Cu_3O_{8+\delta}$ thin films, S.H.H. Naqvi, F. Beech and I.W. Boyd 54 (1992) 166

Synthesis of SiO_2 thin films by reactive excimer laser ablation, E. Fogarassy, A. Slaoui, C. Fuchs and J.P. Stoquert 54 (1992) 180

Ablation of silicate glasses by laser irradiation: modelling and experimental results, C. Buerhop, R. Weissmann and N. Lutz 54 (1992) 187

Excimer laser ablation of fused silica, J. Ihlemann 54 (1992) 193

Laser deposition of copper oxide thin films: contrast with sputtering, C. Ortiz, C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka 54 (1992) 201

Thin film deposition of dielectric oxides by laser ablation, S. Amirhaghi, A. Archer, B. Taguiang, R. McMinn, P. Barnes, S. Tarling and I.W. Boyd 54 (1992) 205

Ablation of hydroxyapatite by pulsed laser irradiation, P. Baeri, L. Torrisi, N. Marino and G. Foti 54 (1992) 210
Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215
Excimer laser ablation of inorganic materials, N. Omori and M. Inoue 54 (1992) 232
Laser ablation processes imaged by high-speed reflection electron microscopy, F. Heinricht and O. Bostanjoglo 54 (1992) 244
Fabrication of nanometer structures using STM, R. Wiesendanger 54 (1992) 271
Properties of Au and Cu layers deposited on photoablated polyphenylquinoxaline surfaces, A. Cros, H. Dallaporta, S. Lazare, H. Hiraoka, N. Merk and W. Marine 54 (1992) 278
Laser projection patterned processing of semiconductors, F. Foulon, M. Green, R.A. Lawes, J. Baker, F.N. Goodall and G. Arthur 54 (1992) 291
Laser-induced nucleation of crystals in amorphous Ge films, O. Bostanjoglo, W. Marine and P. Thomsen-Schmidt 54 (1992) 302
Suitable precursor/solvent systems for laser-induced surface prenucleation, S. Preuss and M. Stuke 54 (1992) 308
Influence of laser assistance on the nucleation and growth processes occurring during the electrodeposition of zinc, I. Zouari, M. Calvo, F. Lapicque and M. Cabrera 54 (1992) 311
Laser-induced structural phase changes in i-carbon films, S. Weissmantel, G. Reisse and S. Schulze 54 (1992) 317
Pulse- and time-dependent observation of UV-laser-induced structures on polymer surfaces, W. Kesting, D. Knittel, T. Bahners and E. Schollmeyer 54 (1992) 330
Laser-assisted engraving of HgCdTe under a liquid layer, M.R. Brook and G.A. Shafeev 54 (1992) 336
Direct carbidation of titanium as a result of multipulse UV-laser irradiation of titanium samples in an ambient methane gas, C. Boulmer-Leborgne, J. Hermann, B. Dubreuil, P. Brault, M.L. DeGiorgi, G. Leggieri, A. Luches, M. Martino, A. Perrone, I.N. Mihailescu, I. Ursu, G. Blondiaux, J.L. Debrun, H. Estrade and B. Rousseau 54 (1992) 349
Multilayer titanium nitride and silicide structures synthesized by multipulse excimer laser irradiation, E. D'Anna, G. Leggieri, A. Luches, M. Martino, A. Perrone, P. Mengucci and I.N. Mihailescu 54 (1992) 353
Laser self-aligned synthesis of $TiSi_2$, V. Craciun, D. Craciun, N. Chitica, I.N. Mihailescu and M. Bertolotti 54 (1992) 362
Laser boronizing of some titanium alloys, C. Badini, M. Bianco, S. Talentino, X.B. Guo and C. Gianoglio 54 (1992) 374
Influence of hydrogen on the structure and surface morphology of pulsed ArF excimer laser crystallized amorphous silicon thin films, E.L. Mathé, A. Naudon, M. Elliq, E. Fogarassy and S. de Unamuno 54 (1992) 392
Laser in-diffusion of Ti in $LiNbO_3$ single crystals, M. Bertolotti, V. Craciun, G. De Cesare, A. Ferrari, A. Jascow, I.N. Mihailescu, G. Mikhailova, A. Cino and M. Rossi 54 (1992) 401
Chemical reactions at metallic and metal/semiconductor interfaces stimulated by pulsed laser annealing, E.J. Petit and R. Caudano 54 (1992) 405
Silent-discharge driven excimer UV sources and their applications, U. Kogelschatz 54 (1992) 410
UV-induced decomposition of adsorbed Cu-acetylacetonate films at room temperature for electroless metal plating, J.-Y. Zhang and H. Esrom 54 (1992) 465
Photoinduced transient reflectance investigation of process-induced near-surface defects in silicon, A. Esser, G. Maidorn and H. Kurz 54 (1992) 482

Ellipsometry

Ablation of thin polymer films on Si or metal substrate with the low intensity UV beam of an excimer laser or mercury lamp: advantages of ellipsometric rate measurements, M. Bolle and S. Lazare 54 (1992) 471
Refractive indices of InAlAs and InGaAs/InP from 250 to 1900 nm determined by spectroscopic ellipsometry, H.W. Dinges, H. Burkhard, R. Lösch, H. Nickel and W. Schlapp 54 (1992) 477

Etching

Laser projection patterned processing of semiconductors, F. Foulon, M. Green,

R.A. Lawes, J. Baker, F.N. Goodall and G. Arthur 54 (1992) 291
Laser-assisted engraving of HgCdTe under a liquid layer, M.R. Brook and G.A. Shafeev 54 (1992) 336

Gallium

Hybrid organometallic compounds of gallium: UV excimer laser photochemistry of $Ga(t\text{-}C_4H_9)_n(CH_3)_{3-n}$ (n = 0, 1, 2, 3), W.M. Cleaver, A.R. Barron, Y. Zhang and M. Stuke 54 (1992) 8

Gallium arsenide

Laser-induced damage formation and tungsten deposition on GaAs, A. Lecours, M. Meunier and R. Izquierdo 54 (1992) 60
Control of the $GaAs/SiO_2$ interface through sulfur passivation and a photo-CVD process, Y. Fujisaki 54 (1992) 95
Excimer laser CVD of silicon oxide on GaAs: a comparison with deposition on c-Si, P. González, E. García, J. Pou, D. Fernández, B. León and M. Pérez-Amor 54 (1992) 108
Excimer laser ablation of inorganic materials, N. Omori and M. Inoue 54 (1992) 232
Laser ablation processes imaged by high-speed reflection electron microscopy, F. Heinricht and O. Bostanjoglo 54 (1992) 244
Laser projection patterned processing of semiconductors, F. Foulon, M. Green, R.A. Lawes, J. Baker, F.N. Goodall and G. Arthur 54 (1992) 291
Intriguing properties of pulsed laser beam mixed Au/Te/Au/GaAs ohmic contacts, K. Wuyts, J. Watté and R.E. Silverans 54 (1992) 366
Refractive indices of InAlAs and InGaAs/InP from 250 to 1900 nm determined by spectroscopic ellipsometry, H.W. Dinges, H. Burkhard, R. Lösch, H. Nickel and W. Schlapp 54 (1992) 477
Laser–surface diagnostics of GaAs growth processes. I. The influence of surface contamination upon optical second harmonic generation from GaAs (100) surfaces, M.E. Pemble, A. Stafford and A.G. Taylor 54 (1992) 490
Laser–surface diagnostics of GaAs growth processes. II. Reflectance anisotropy studies of GaAs growth by MBE, S.R. Armstrong, M.E. Pemble, A.G. Taylor, B.A. Joyce, J.H. Neave, J. Zhang and D.A. Klug 54 (1992) 493
Investigation of a semiconductor superlattice by use of grazing incidence X-ray diffraction, U. Pietsch, W. Seifert, J.-O. Fornell, H. Rhan, H. Metzger, S. Rugel and J. Peisl 54 (1992) 502

Germanium

Laser ablation of Ge in an oxygen environment: plasma and film properties, C.N. Afonso, F. Vega, J. Solis, F. Catalina, C. Ortega and J. Siejka 54 (1992) 175
Laser-induced nucleation of crystals in amorphous Ge films, O. Bostanjoglo, W. Marine and P. Thomsen-Schmidt 54 (1992) 302
UV-laser-induced oxidation kinetics of c-Ge: transient reflectivity study, F. Vega, C.N. Afonso, J. Solis, R. Serna and C. Ortiz 54 (1992) 341
Excimer laser induced surface modification of thin Ge–Se films, A. Jadin, M. Wautelet and L.D. Laude 54 (1992) 345

Glass

Ablation of silicate glasses by laser irradiation: modelling and experimental results, C. Buerhop, R. Weissmann and N. Lutz 54 (1992) 187
Excimer laser ablation of fused silica, J. Ihlemann 54 (1992) 193

Gold

Laser induced CVD of gold using new precursors, J. Messelhäuser, E.B. Flint and H. Suhr 54 (1992) 64
Multishot ablation of polymer and metal films at 248 nm, E. Hunger, H. Pietsch, S. Petzoldt and E. Matthias 54 (1992) 227
Laser ablation processes imaged by high-speed reflection electron microscopy, F. Heinricht and O. Bostanjoglo 54 (1992) 244
Properties of Au and Cu layers deposited on photoablated polyphenylquinoxaline surfaces, A. Cros, H. Dallaporta, S. Lazare, H. Hiraoka, N. Merk and W. Marine 54 (1992) 278
Intriguing properties of pulsed laser beam mixed Au/Te/Au/GaAs ohmic con-

tacts, K. Wuyts, J. Watté and R.E. Silverans 54 (1992) 366

Hydrogen

Laser–surface diagnostics of GaAs growth processes. I. The influence of surface contamination upon optical second harmonic generation from GaAs (100) surfaces, M.E. Pemble, A. Stafford and A.G. Taylor 54 (1992) 490

Indium arsenide

Refractive indices of InAlAs and InGaAs/InP from 250 to 1900 nm determined by spectroscopic ellipsometry, H.W. Dinges, H. Burkhard, R. Lösch, H. Nickel and W. Schlapp 54 (1992) 477
Investigation of a semiconductor superlattice by use of grazing incidence X-ray diffraction, U. Pietsch, W. Seifert, J.-O. Fornell, H. Rhan, H. Metzger, S. Rugel and J. Peisl 54 (1992) 502

Indium phosphide

Refractive indices of InAlAs and InGaAs/InP from 250 to 1900 nm determined by spectroscopic ellipsometry, H.W. Dinges, H. Burkhard, R. Lösch, H. Nickel and W. Schlapp 54 (1992) 477
Investigation of a semiconductor superlattice by use of grazing incidence X-ray diffraction, U. Pietsch, W. Seifert, J.-O. Fornell, H. Rhan, H. Metzger, S. Rugel and J. Peisl 54 (1992) 502

Infrared spectroscopy

Hybrid organometallic compounds of gallium: UV excimer laser photochemistry of $Ga(t\text{-}C_4H_9)_n(CH_3)_{3-n}$ (n = 0, 1, 2, 3), W.M. Cleaver, A.R. Barron, Y. Zhang and M. Stuke 54 (1992) 8
ArF laser induced CVD of SiO_2 films: a search for the best suitable precursors, D. Rieger and F. Bachmann 54 (1992) 99
Excimer laser CVD of silicon oxide on GaAs: a comparison with deposition on c-Si, P. González, E. García, J. Pou, D. Fernández, B. León and M. Pérez-Amor 54 (1992) 108
Low-temperature silicon oxide films deposited using a CO_2 laser, D. Fernández, P. González, J. Pou, B. León and M. Pérez-Amor 54 (1992) 112
Deposition of SiON by ArF laser CVD, A. Löffler-Peters, J. Müller and T. Ebert 54 (1992) 121
Rapid thermal chemical vapour deposition of SiO_xN_y films, F. Lebland, C. Licoppe, Y. Gao, Y.I. Nissim and S. Rigo 54 (1992) 125
Synthesis of SiO_2 thin films by reactive excimer laser ablation, E. Fogarassy, A. Slaoui, C. Fuchs and J.P. Stoquert 54 (1992) 180
UV annealing of low temperature photodeposited SiO_2 films with a new powerful lamp source, C. Debauche, C. Licoppe, C. Meriadec, F. Sartoris and J. Flicstein 54 (1992) 435
Surface mechanisms in the UVCVD of SiO_2 films, C. Licoppe, C. Meriadec, Y.I. Nissim and J.M. Moison 54 (1992) 445

Inorganic compounds

Excimer laser ablation of inorganic materials, N. Omori and M. Inoue 54 (1992) 232
Laser in-diffusion of Ti in $LiNbO_3$ single crystals, M. Bertolotti, V. Craciun, G. De Cesare, A. Ferrari, A. Jascow, I.N. Mihailescu, G. Mikhailova, A. Cino and M. Rossi 54 (1992) 401

Ion implantation

Potential of photon and particle beams for surface treatment of thin ceramic coatings, J.P. Celis, M. Franck, J.R. Roos, E.W. Kreutz, A. Gasser, M. Wehner, K. Wissenbach and N. Pattyn 54 (1992) 322
Grazing incidence X-ray diffraction on silicon after ion implantation and thermal annealing, S. Rugel, H. Metzger, G. Wallner and J. Peisl 54 (1992) 507

Ion scattering

One-step growth of polycrystalline silicon thin films at low-temperature by ArF excimer laser-induced photo-CVD, M. Elliq, E. Fogarassy, C. Fuchs, J.P. Stoquert, S. de Unamuno, B. Prévot and E.L. Mathé 54 (1992) 35
Study of laser ablation of BiSrCaCuO, R. Pérez Casero, F. Kerhervé, J.P. Enard, J. Perrière and P. Regnier 54 (1992) 147

Synthesis of SiO_2 thin films by reactive excimer laser ablation, E. Fogarassy, A. Slaoui, C. Fuchs and J.P. Stoquert 54 (1992) 180
Laser deposition of copper oxide thin films: contrast with sputtering, C. Ortiz, C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka 54 (1992) 201
Ablation of hydroxyapatite by pulsed laser irradiation, P. Baeri, L. Torrisi, N. Marino and G. Foti 54 (1992) 210
Potential of photon and particle beams for surface treatment of thin ceramic coatings, J.P. Celis, M. Franck, J.R. Roos, E.W. Kreutz, A. Gasser, M. Wehner, K. Wissenbach and N. Pattyn 54 (1992) 322
Direct carbidation of titanium as a result of multipulse UV-laser irradiation of titanium samples in an ambient methane gas, C. Boulmer-Leborgne, J. Hermann, B. Dubreuil, P. Brault, M.L. DeGiorgi, G. Leggieri, A. Luches, M. Martino, A. Perrone, I.N. Mihailescu, I. Ursu, G. Blondiaux, J.L. Debrun, H. Estrade and B. Rousseau 54 (1992) 349
Multilayer titanium nitride and silicide structures synthesized by multipulse excimer laser irradiation, E. D'Anna, G. Leggieri, A. Luches, M. Martino, A. Perrone, P. Mengucci and I.N. Mihailescu 54 (1992) 353
Intriguing properties of pulsed laser beam mixed Au/Te/Au/GaAs ohmic contacts, K. Wuyts, J. Watté and R.E. Silverans 54 (1992) 366
Non-equilibrium epitaxial silicides – a special effect of silicide formation by ns-laser irradiation, B. Weber, K. Gärtner, A. Witzmann, C. Kaschner and I. Kasko 54 (1992) 381
Influence of hydrogen on the structure and surface morphology of pulsed ArF excimer laser crystallized amorphous silicon thin films, E.L. Mathé, A. Naudon, M. Elliq, E. Fogarassy and S. de Unamuno 54 (1992) 392
Laser in-diffusion of Ti in $LiNbO_3$ single crystals, M. Bertolotti, V. Craciun, G. De Cesare, A. Ferrari, A. Jascow, I.N. Mihailescu, G. Mikhailova, A. Cino and M. Rossi 54 (1992) 401
Chemical reactions at metallic and metal/semiconductor interfaces stimulated by pulsed laser annealing, E.J. Petit and R. Caudano 54 (1992) 405
Sensitivity of a modulated optical reflectance probe to process-induced lattice disorder, M. Murtagh, G.M. Crean, T. Flaherty and C. Jeynes 54 (1992) 497

Iron

Non-equilibrium epitaxial silicides – a special effect of silicide formation by ns-laser irradiation, B. Weber, K. Gärtner, A. Witzmann, C. Kaschner and I. Kasko 54 (1992) 381

Laser processing

Photodecomposition of precursors for metal organic vapour phase epitaxy, W. Richter, P. Kurpas and M. Waschbüsch 54 (1992) 1
Hybrid organometallic compounds of gallium: UV excimer laser photochemistry of $Ga(t\text{-}C_4H_9)_n(CH_3)_{3-n}$ (n = 0, 1, 2, 3), W.M. Cleaver, A.R. Barron, Y. Zhang and M. Stuke 54 (1992) 8
Laser-induced deposition of one-micron-size polysilicon lines from mono and trisilane, S. Boughaba and G. Auvert 54 (1992) 25
CW CO_2 laser CVD of amorphous hydrogenated silicon (a-Si:H): influence of the deposition geometry, E. Golusda, R. Lange, K.-D. Lühmann, G. Mollekopf, M. Wacker and H. Stafast 54 (1992) 30
One-step growth of polycrystalline silicon thin films at low-temperature by ArF excimer laser-induced photo-CVD, M. Elliq, E. Fogarassy, C. Fuchs, J.P. Stoquert, S. de Unamuno, B. Prévot and E.L. Mathé 54 (1992) 35
Theoretical and experimental studies of laser-induced chemical vapour deposition of silicon thin films, A. Fischer, G. Reisse, F. Gänsicke and K. Zimmer 54 (1992) 41
Spectroscopic investigations of gas-phase chemistry during laser-induced photolytic CVD of W, P. Mogyorósi, J.O. Carlsson and M. Moradi 54 (1992) 46
Modeling KrF excimer laser induced deposition of titanium from titanium tetrachloride, M. Meunier, C. Lavoie, S. Boivin, R. Izquierdo and P. Desjardins 54 (1992) 52
Laser-induced chemical vapor deposition of rhodium, E.B. Flint, J. Messelhäuser and H. Suhr 54 (1992) 56
Laser-induced damage formation and tungsten deposition on GaAs, A.

Lecours, M. Meunier and R. Izquierdo 54 (1992) 60
Laser induced CVD of gold using new precursors, J. Messelhäuser, E.B. Flint and H. Suhr 54 (1992) 64
Reactive TiN deposition on alloys with laser radiation, E.W. Kreutz, M. Krösche, H. Sung, A. Voss and K. Wissenbach 54 (1992) 69
Reactive pulsed laser deposition of TiN, D. Craciun and V. Craciun 54 (1992) 75
IR-laser CVD of TiB_2, TiC_x and TiC_xN_y coatings on carbon fibres, V. Hopfe, A. Tehel, A. Baier and J. Scharsig 54 (1992) 78
Laser-induced chemical vapour deposition of conductive and insulating thin films, G. Reisse, F. Gaensicke, R. Ebert, U. Illmann and H. Johansen 54 (1992) 84
Excimer laser photolysis of metalorganic complexes of platinum and palladium in the gas phase, H. Willwohl and J. Wolfrum 54 (1992) 89
ArF laser induced CVD of SiO_2 films: a search for the best suitable precursors, D. Rieger and F. Bachmann 54 (1992) 99
Excimer laser CVD of silicon oxide on GaAs: a comparison with deposition on c-Si, P. González, E. García, J. Pou, D. Fernández, B. León and M. Pérez-Amor 54 (1992) 108
Low-temperature silicon oxide films deposited using a CO_2 laser, D. Fernández, P. González, J. Pou, B. León and M. Pérez-Amor 54 (1992) 112
Kinetics of excimer-laser induced CVD of W, R.L. Krans, C. Brands and W.C. Sinke 54 (1992) 117
Deposition of SiON by ArF laser CVD, A. Löffler-Peters, J. Müller and T. Ebert 54 (1992) 121
CO_2 laser induced CVD of TiN, O. Conde, M.L.G. Ferreira, P. Hochholdinger, A.J. Silvestre and R. Vilar 54 (1992) 130
Laser-induced chemical vapor deposition of titanium diboride, J. Elders and J.D.W. van Voorst 54 (1992) 135
Deposition of ceramics by LPVD, J. Funken, E.W. Kreutz, M. Krösche, H. Sung, A. Voss, G. Erkens, O. Lemmer and T. Leyendecker 54 (1992) 141
Study of laser ablation of BiSrCaCuO, R. Pérez Casero, F. Kerhervé, J.P. Enard, J. Perrière and P. Regnier 54 (1992) 147
Laser ablation deposition of PbO/Bi-PbSrCaCuO, A. Sajjadi, M.K. Yau, F. Saba, F. Beech and I.W. Boyd 54 (1992) 154
Ablation studies of Y–Ba–Cu–oxide in oxygen using a pulsed CO_2 laser, P.E. Dyer, P.H. Key and P. Monk 54 (1992) 160
In-situ and multilayer laser ablation deposition of $Pb_2Sr_2Y_{0.5}Ca_{0.5}Cu_3O_{8+\delta}$ thin films, S.H.H. Naqvi, F. Beech and I.W. Boyd 54 (1992) 166
Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171
Laser ablation of Ge in an oxygen environment: plasma and film properties, C.N. Afonso, F. Vega, J. Solis, F. Catalina, C. Ortega and J. Siejka 54 (1992) 175
Synthesis of SiO_2 thin films by reactive excimer laser ablation, E. Fogarassy, A. Slaoui, C. Fuchs and J.P. Stoquert 54 (1992) 180
Ablation of silicate glasses by laser irradiation: modelling and experimental results, C. Buerhop, R. Weissmann and N. Lutz 54 (1992) 187
Excimer laser ablation of fused silica, J. Ihlemann 54 (1992) 193
Laser deposition of copper oxide thin films: contrast with sputtering, C. Ortiz, C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka 54 (1992) 201
Thin film deposition of dielectric oxides by laser ablation, S. Amirhaghi, A. Archer, B. Taguiang, R. McMinn, P. Barnes, S. Tarling and I.W. Boyd 54 (1992) 205
Ablation of hydroxyapatite by pulsed laser irradiation, P. Baeri, L. Torrisi, N. Marino and G. Foti 54 (1992) 210
Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215
Multishot ablation of polymer and metal films at 248 nm, E. Hunger, H. Pietsch, S. Petzoldt and E. Matthias 54 (1992) 227
Excimer laser ablation of inorganic materials, N. Omori and M. Inoue 54 (1992) 232
Laser ablation of dyes, M. Späth and M. Stuke 54 (1992) 237
Photoablation of polymers, P. Lemoine and W. Blau 54 (1992) 240
Laser ablation processes imaged by high-speed reflection electron microscopy, F. Heinricht and O. Bostanjoglo 54 (1992) 244
Fast time-response photoacoustic studies and modelling of KrF laser ablated $YBa_2Cu_3O_7$, P.E. Dyer, S.R. Farrar and P.H. Key 54 (1992) 255
Analysis of the plasma expansion dynam-

ics by optical time-of-flight measurements, W. Marine, M. Gerri, J.M. Scotto d'Aniello, M. Sentis, Ph. Delaporte, B. Forestier and B. Fontaine 54 (1992) 264
Properties of Au and Cu layers deposited on photoablated polyphenylquinoxaline surfaces, A. Cros, H. Dallaporta, S. Lazare, H. Hiraoka, N. Merk and W. Marine 54 (1992) 278
Laser projection patterned processing of semiconductors, F. Foulon, M. Green, R.A. Lawes, J. Baker, F.N. Goodall and G. Arthur 54 (1992) 291
Laser-induced nucleation of crystals in amorphous Ge films, O. Bostanjoglo, W. Marine and P. Thomsen-Schmidt 54 (1992) 302
Suitable precursor/solvent systems for laser-induced surface prenucleation, S. Preuss and M. Stuke 54 (1992) 308
Influence of laser assistance on the nucleation and growth processes occurring during the electrodeposition of zinc, I. Zouari, M. Calvo, F. Lapicque and M. Cabrera 54 (1992) 311
Laser-induced structural phase changes in i-carbon films, S. Weissmantel, G. Reisse and S. Schulze 54 (1992) 317
Potential of photon and particle beams for surface treatment of thin ceramic coatings, J.P. Celis, M. Franck, J.R. Roos, E.W. Kreutz, A. Gasser, M. Wehner, K. Wissenbach and N. Pattyn 54 (1992) 322
Pulse- and time-dependent observation of UV-laser-induced structures on polymer surfaces, W. Kesting, D. Knittel, T. Bahners and E. Schollmeyer 54 (1992) 330
Laser-assisted engraving of HgCdTe under a liquid layer, M.R. Brook and G.A. Shafeev 54 (1992) 336
UV-laser-induced oxidation kinetics of c-Ge: transient reflectivity study, F. Vega, C.N. Afonso, J. Solis, R. Serna and C. Ortiz 54 (1992) 341
Excimer laser induced surface modification of thin Ge–Se films, A. Jadin, M. Wautelet and L.D. Laude 54 (1992) 345
Direct carbidation of titanium as a result of multipulse UV-laser irradiation of titanium samples in an ambient methane gas, C. Boulmer-Leborgne, J. Hermann, B. Dubreuil, P. Brault, M.L. DeGiorgi, G. Leggieri, A. Luches, M. Martino, A. Perrone, I.N. Mihailescu, I. Ursu, G. Blondiaux, J.L. Debrun, H. Estrade and B. Rousseau 54 (1992) 349
Multilayer titanium nitride and silicide structures synthesized by multipulse excimer laser irradiation, E. D'Anna, G. Leggieri, A. Luches, M. Martino, A. Perrone, P. Mengucci and I.N. Mihailescu 54 (1992) 353
CW-laser-induced synthesis of Sb_2Se_3 thin films, K. Kolev and L.D. Laude 54 (1992) 358
Laser self-aligned synthesis of $TiSi_2$, V. Craciun, D. Craciun, N. Chitica, I.N. Mihailescu and M. Bertolotti 54 (1992) 362
Intriguing properties of pulsed laser beam mixed Au/Te/Au/GaAs ohmic contacts, K. Wuyts, J. Watté and R.E. Silverans 54 (1992) 366
Laser boronizing of some titanium alloys, C. Badini, M. Bianco, S. Talentino, X.B. Guo and C. Gianoglio 54 (1992) 374
Non-equilibrium epitaxial silicides – a special effect of silicide formation by ns-laser irradiation, B. Weber, K. Gärtner, A. Witzmann, C. Kaschner and I. Kasko 54 (1992) 381
Comparison of laser and line-electron beam recrystallization of thin polycrystalline silicon films, M. Pauli, G. Dähn and J. Müller 54 (1992) 386
Influence of hydrogen on the structure and surface morphology of pulsed ArF excimer laser crystallized amorphous silicon thin films, E.L. Mathé, A. Naudon, M. Elliq, E. Fogarassy and S. de Unamuno 54 (1992) 392
Laser in-diffusion of Ti in $LiNbO_3$ single crystals, M. Bertolotti, V. Craciun, G. De Cesare, A. Ferrari, A. Jascow, I.N. Mihailescu, G. Mikhailova, A. Cino and M. Rossi 54 (1992) 401
Chemical reactions at metallic and metal/semiconductor interfaces stimulated by pulsed laser annealing, E.J. Petit and R. Caudano 54 (1992) 405
UV-induced decomposition of adsorbed Cu-acetylacetonate films at room temperature for electroless metal plating, J.-Y. Zhang and H. Esrom 54 (1992) 465
Ablation of thin polymer films on Si or metal substrate with the low intensity UV beam of an excimer laser or mercury lamp: advantages of ellipsometric rate measurements, M. Bolle and S. Lazare 54 (1992) 471
Photoinduced transient reflectance investigation of process-induced near-

surface defects in silicon, A. Esser, G. Maidorn and H. Kurz 54 (1992) 482

Lead oxide

Laser ablation deposition of PbO/Bi-PbSrCaCuO, A. Sajjadi, M.K. Yau, F. Saba, F. Beech and I.W. Boyd 54 (1992) 154

Light scattering

Kinetics of excimer-laser induced CVD of W, R.L. Krans, C. Brands and W.C. Sinke 54 (1992) 117
Photoinduced transient reflectance investigation of process-induced near-surface defects in silicon, A. Esser, G. Maidorn and H. Kurz 54 (1992) 482

Luminescence

Spectroscopic investigations of gas-phase chemistry during laser-induced photolytic CVD of W, P. Mogyorósi, J.O. Carlsson and M. Moradi 54 (1992) 46
Excimer laser photolysis of metalorganic complexes of platinum and palladium in the gas phase, H. Willwohl and J. Wolfrum 54 (1992) 89
Laser ablation of Ge in an oxygen environment: plasma and film properties, C.N. Afonso, F. Vega, J. Solis, F. Catalina, C. Ortega and J. Siejka 54 (1992) 175
Laser ablation of dyes, M. Späth and M. Stuke 54 (1992) 237

Mass spectroscopy

Hybrid organometallic compounds of gallium: UV excimer laser photochemistry of $Ga(t\text{-}C_4H_9)_n(CH_3)_{3-n}$ (n = 0, 1, 2, 3), W.M. Cleaver, A.R. Barron, Y. Zhang and M. Stuke 54 (1992) 8
Identification of the gas-phase products which occur during the deposition of AlN using the organometallic precursor: $[(CH_3)_2AlNH_2]_3$, C.C. Amato, J.B. Hudson and L.V. Interrante 54 (1992) 18
Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171
Ablation of hydroxyapatite by pulsed laser irradiation, P. Baeri, L. Torrisi, N. Marino and G. Foti 54 (1992) 210

Mercury telluride

Laser-assisted engraving of HgCdTe under a liquid layer, M.R. Brook and G.A. Shafeev 54 (1992) 336

Molecular beam epitaxy

Refractive indices of InAlAs and InGaAs/InP from 250 to 1900 nm determined by spectroscopic ellipsometry, H.W. Dinges, H. Burkhard, R. Lösch, H. Nickel and W. Schlapp 54 (1992) 477
Laser–surface diagnostics of GaAs growth processes. II. Reflectance anisotropy studies of GaAs growth by MBE, S.R. Armstrong, M.E. Pemble, A.G. Taylor, B.A. Joyce, J.H. Neave, J. Zhang and D.A. Klug 54 (1992) 493

Molybdenum

Laser-induced chemical vapour deposition of conductive and insulating thin films, G. Reisse, F. Gaensicke, R. Ebert, U. Illmann and H. Johansen 54 (1992) 84

Mössbauer spectroscopy

Intriguing properties of pulsed laser beam mixed Au/Te/Au/GaAs ohmic contacts, K. Wuyts, J. Watté and R.E. Silverans 54 (1992) 366

Nickel

Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171
Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215
Multishot ablation of polymer and metal films at 248 nm, E. Hunger, H. Pietsch, S. Petzoldt and E. Matthias 54 (1992) 227
Non-equilibrium epitaxial silicides – a special effect of silicide formation by ns-laser irradiation, B. Weber, K. Gärtner, A. Witzmann, C. Kaschner and I. Kasko 54 (1992) 381

Nitrides

Identification of the gas-phase products which occur during the deposition of AlN using the organometallic precursor: $[(CH_3)_2AlNH_2]_3$, C.C. Amato, J.B. Hudson and L.V. Interrante 54 (1992) 18

Reactive TiN deposition on alloys with laser radiation, E.W. Kreutz, M. Krösche, H. Sung, A. Voss and K. Wissenbach 54 (1992) 69

Reactive pulsed laser deposition of TiN, D. Craciun and V. Craciun 54 (1992) 75

IR-laser CVD of TiB_2, TiC_x and TiC_xN_y coatings on carbon fibres, V. Hopfe, A. Tehel, A. Baier and J. Scharsig 54 (1992) 78

CO_2 laser induced CVD of TiN, O. Conde, M.L.G. Ferreira, P. Hochholdinger, A.J. Silvestre and R. Vilar 54 (1992) 130

Potential of photon and particle beams for surface treatment of thin ceramic coatings, J.P. Celis, M. Franck, J.R. Roos, E.W. Kreutz, A. Gasser, M. Wehner, K. Wissenbach and N. Pattyn 54 (1992) 322

Multilayer titanium nitride and silicide structures synthesized by multipulse excimer laser irradiation, E. D'Anna, G. Leggieri, A. Luches, M. Martino, A. Perrone, P. Mengucci and I.N. Mihailescu 54 (1992) 353

Optical properties

ArF laser induced CVD of SiO_2 films: a search for the best suitable precursors, D. Rieger and F. Bachmann 54 (1992) 99

Excimer laser CVD of silicon oxide on GaAs: a comparison with deposition on c-Si, P. González, E. García, J. Pou, D. Fernández, B. León and M. Pérez-Amor 54 (1992) 108

Low-temperature silicon oxide films deposited using a CO_2 laser, D. Fernández, P. González, J. Pou, B. León and M. Pérez-Amor 54 (1992) 112

Deposition of SiON by ArF laser CVD, A. Löffler-Peters, J. Müller and T. Ebert 54 (1992) 121

Rapid thermal chemical vapour deposition of SiO_xN_y films, F. Lebland, C. Licoppe, Y. Gao, Y.I. Nissim and S. Rigo 54 (1992) 125

Laser deposition of copper oxide thin films: contrast with sputtering, C. Ortiz, C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka 54 (1992) 201

Photoablation of polymers, P. Lemoine and W. Blau 54 (1992) 240

Pulse- and time-dependent observation of UV-laser-induced structures on polymer surfaces, W. Kesting, D. Knittel, T. Bahners and E. Schollmeyer 54 (1992) 330

UV-laser-induced oxidation kinetics of c-Ge: transient reflectivity study, F. Vega, C.N. Afonso, J. Solis, R. Serna and C. Ortiz 54 (1992) 341

CW-laser-induced synthesis of Sb_2Se_3 thin films, K. Kolev and L.D. Laude 54 (1992) 358

Influence of hydrogen on the structure and surface morphology of pulsed ArF excimer laser crystallized amorphous silicon thin films, E.L. Mathé, A. Naudon, M. Elliq, E. Fogarassy and S. de Unamuno 54 (1992) 392

Metal deposition with a windowless VUV excimer source, H. Esrom and U. Kogelschatz 54 (1992) 440

Ablation of thin polymer films on Si or metal substrate with the low intensity UV beam of an excimer laser or mercury lamp: advantages of ellipsometric rate measurements, M. Bolle and S. Lazare 54 (1992) 471

Refractive indices of InAlAs and InGaAs/InP from 250 to 1900 nm determined by spectroscopic ellipsometry, H.W. Dinges, H. Burkhard, R. Lösch, H. Nickel and W. Schlapp 54 (1992) 477

Laser–surface diagnostics of GaAs growth processes. II. Reflectance anisotropy studies of GaAs growth by MBE, S.R. Armstrong, M.E. Pemble, A.G. Taylor, B.A. Joyce, J.H. Neave, J. Zhang and D.A. Klug 54 (1992) 493

Sensitivity of a modulated optical reflectance probe to process-induced lattice disorder, M. Murtagh, G.M. Crean, T. Flaherty and C. Jeynes 54 (1992) 497

Organic substances

Laser ablation of dyes, M. Späth and M. Stuke 54 (1992) 237

Suitable precursor/solvent systems for laser-induced surface prenucleation, S. Preuss and M. Stuke 54 (1992) 308

Metal deposition with a windowless VUV excimer source, H. Esrom and U. Kogelschatz 54 (1992) 440

Improvement of the SiO_2 deposition by 185 nm photolysis of N_2O and SiH_4 by addition of neopentane, M. Petit-

jean, N. Proust, J.-F. Chapeaublanc and J. Perrin 54 (1992) 453

Organometallic vapour deposition

Photodecomposition of precursors for metal organic vapour phase epitaxy, W. Richter, P. Kurpas and M. Waschbüsch 54 (1992) 1
Hybrid organometallic compounds of gallium: UV excimer laser photochemistry of $Ga(t\text{-}C_4H_9)_n(CH_3)_{3-n}$ (n = 0, 1, 2, 3), W.M. Cleaver, A.R. Barron, Y. Zhang and M. Stuke 54 (1992) 8
Identification of the gas-phase products which occur during the deposition of AlN using the organometallic precursor: $[(CH_3)_2AlNH_2]_3$, C.C. Amato, J.B. Hudson and L.V. Interrante 54 (1992) 18
Laser-induced chemical vapor deposition of rhodium, E.B. Flint, J. Messelhäuser and H. Suhr 54 (1992) 56
Laser induced CVD of gold using new precursors, J. Messelhäuser, E.B. Flint and H. Suhr 54 (1992) 64
Excimer laser photolysis of metalorganic complexes of platinum and palladium in the gas phase, H. Willwohl and J. Wolfrum 54 (1992) 89
UV-induced decomposition of adsorbed Cu-acetylacetonate films at room temperature for electroless metal plating, J.-Y. Zhang and H. Esrom 54 (1992) 465
Investigation of a semiconductor superlattice by use of grazing incidence X-ray diffraction, U. Pietsch, W. Seifert, J.-O. Fornell, H. Rhan, H. Metzger, S. Rugel and J. Peisl 54 (1992) 502

Oxidation

UV-laser-induced oxidation kinetics of c-Ge: transient reflectivity study, F. Vega, C.N. Afonso, J. Solis, R. Serna and C. Ortiz 54 (1992) 341
Low temperature photo-assisted oxidation of silicon, A. Kazor and I.W. Boyd 54 (1992) 460

Oxides

Thin film deposition of dielectric oxides by laser ablation, S. Amirhaghi, A. Archer, B. Taguiang, R. McMinn, P. Barnes, S. Tarling and I.W. Boyd 54 (1992) 205

Oxygen

Laser desorption on Si surfaces by use of multiple excimer laser pulses, H. Schlemm, F. Buchmann and H.-D. Geiler 54 (1992) 298

Palladium

Excimer laser photolysis of metalorganic complexes of platinum and palladium in the gas phase, H. Willwohl and J. Wolfrum 54 (1992) 89
Suitable precursor/solvent systems for laser-induced surface prenucleation, S. Preuss and M. Stuke 54 (1992) 308
Silent-discharge driven excimer UV sources and their applications, U. Kogelschatz 54 (1992) 410
Metal deposition with a windowless VUV excimer source, H. Esrom and U. Kogelschatz 54 (1992) 440

Photodesorption

Laser desorption on Si surfaces by use of multiple excimer laser pulses, H. Schlemm, F. Buchmann and H.-D. Geiler 54 (1992) 298

Photoelectron spectroscopy

Reactive pulsed laser deposition of TiN, D. Craciun and V. Craciun 54 (1992) 75
Control of the $GaAs/SiO_2$ interface through sulfur passivation and a photo-CVD process, Y. Fujisaki 54 (1992) 95
Excimer laser ablation of inorganic materials, N. Omori and M. Inoue 54 (1992) 232
Properties of Au and Cu layers deposited on photoablated polyphenylquinoxaline surfaces, A. Cros, H. Dallaporta, S. Lazare, H. Hiraoka, N. Merk and W. Marine 54 (1992) 278
Excimer laser induced surface modification of thin Ge–Se films, A. Jadin, M. Wautelet and L.D. Laude 54 (1992) 345
Direct carbidation of titanium as a result of multipulse UV-laser irradiation of titanium samples in an ambient methane gas, C. Boulmer-Leborgne, J. Hermann, B. Dubreuil, P. Brault, M.L. DeGiorgi, G. Leggieri, A. Luches, M. Martino, A. Perrone, I.N. Mihailescu, I. Ursu, G. Blondiaux,

J.L. Debrun, H. Estrade and B. Rousseau 54 (1992) 349

Photon emission

Silent-discharge driven excimer UV sources and their applications, U. Kogelschatz 54 (1992) 410
Development of a novel large area excimer lamp for direct photo deposition of thin films, P. Bergonzo, P. Patel, I.W. Boyd and U. Kogelschatz 54 (1992) 424
VUV excimer light source for deposition of amorphous semiconductors, F. Kessler and G.H. Bauer 54 (1992) 430
Metal deposition with a windowless VUV excimer source, H. Esrom and U. Kogelschatz 54 (1992) 440

Platinum

Excimer laser photolysis of metalorganic complexes of platinum and palladium in the gas phase, H. Willwohl and J. Wolfrum 54 (1992) 89

Polymers

Multishot ablation of polymer and metal films at 248 nm, E. Hunger, H. Pietsch, S. Petzoldt and E. Matthias 54 (1992) 227
Photoablation of polymers, P. Lemoine and W. Blau 54 (1992) 240
Properties of Au and Cu layers deposited on photoablated polyphenylquinoxaline surfaces, A. Cros, H. Dallaporta, S. Lazare, H. Hiraoka, N. Merk and W. Marine 54 (1992) 278
Pulse- and time-dependent observation of UV-laser-induced structures on polymer surfaces, W. Kesting, D. Knittel, T. Bahners and E. Schollmeyer 54 (1992) 330
Silent-discharge driven excimer UV sources and their applications, U. Kogelschatz 54 (1992) 410
Ablation of thin polymer films on Si or metal substrate with the low intensity UV beam of an excimer laser or mercury lamp: advantages of ellipsometric rate measurements, M. Bolle and S. Lazare 54 (1992) 471

Radiation damage

Sensitivity of a modulated optical reflectance probe to process-induced lattice disorder, M. Murtagh, G.M. Crean, T. Flaherty and C. Jeynes 54 (1992) 497

Raman scattering

Photodecomposition of precursors for metal organic vapour phase epitaxy, W. Richter, P. Kurpas and M. Waschbüsch 54 (1992) 1
One-step growth of polycrystalline silicon thin films at low-temperature by ArF excimer laser-induced photo-CVD, M. Elliq, E. Fogarassy, C. Fuchs, J.P. Stoquert, S. de Unamuno, B. Prévot and E.L. Mathé 54 (1992) 35

Rhodium

Laser-induced chemical vapor deposition of rhodium, E.B. Flint, J. Messelhäuser and H. Suhr 54 (1992) 56

Second harmonic generation

Laser–surface diagnostics of GaAs growth processes. I. The influence of surface contamination upon optical second harmonic generation from GaAs (100) surfaces, M.E. Pemble, A. Stafford and A.G. Taylor 54 (1992) 490

Secondary ion mass spectroscopy

Direct carbidation of titanium as a result of multipulse UV-laser irradiation of titanium samples in an ambient methane gas, C. Boulmer-Leborgne, J. Hermann, B. Dubreuil, P. Brault, M.L. DeGiorgi, G. Leggieri, A. Luches, M. Martino, A. Perrone, I.N. Mihailescu, I. Ursu, G. Blondiaux, J.L. Debrun, H. Estrade and B. Rousseau 54 (1992) 349
Laser in-diffusion of Ti in $LiNbO_3$ single crystals, M. Bertolotti, V. Craciun, G. De Cesare, A. Ferrari, A. Jascow, I.N. Mihailescu, G. Mikhailova, A. Cino and M. Rossi 54 (1992) 401

Selenium

Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171

Excimer laser induced surface modification of thin Ge–Se films, A. Jadin, M. Wautelet and L.D. Laude 54 (1992) 345

CW-laser-induced synthesis of Sb_2Se_3 thin films, K. Kolev and L.D. Laude 54 (1992) 358

Silicides

Laser-induced chemical vapour deposition of conductive and insulating thin films, G. Reisse, F. Gaensicke, R. Ebert, U. Illmann and H. Johansen 54 (1992) 84

Multilayer titanium nitride and silicide structures synthesized by multipulse excimer laser irradiation, E. D'Anna, G. Leggieri, A. Luches, M. Martino, A. Perrone, P. Mengucci and I.N. Mihailescu 54 (1992) 353

Laser self-aligned synthesis of $TiSi_2$, V. Craciun, D. Craciun, N. Chitica, I.N. Mihailescu and M. Bertolotti 54 (1992) 362

Non-equilibrium epitaxial silicides – a special effect of silicide formation by ns-laser irradiation, B. Weber, K. Gärtner, A. Witzmann, C. Kaschner and I. Kasko 54 (1992) 381

Silicon

Laser-induced deposition of one-micron-size polysilicon lines from mono and trisilane, S. Boughaba and G. Auvert 54 (1992) 25

CW CO_2 laser CVD of amorphous hydrogenated silicon (a-Si:H): influence of the deposition geometry, E. Golusda, R. Lange, K.-D. Lühmann, G. Mollekopf, M. Wacker and H. Stafast 54 (1992) 30

One-step growth of polycrystalline silicon thin films at low-temperature by ArF excimer laser-induced photo-CVD, M. Elliq, E. Fogarassy, C. Fuchs, J.P. Stoquert, S. de Unamuno, B. Prévot and E.L. Mathé 54 (1992) 35

Theoretical and experimental studies of laser-induced chemical vapour deposition of silicon thin films, A. Fischer, G. Reisse, F. Gänsicke and K. Zimmer 54 (1992) 41

Laser ablation processes imaged by high-speed reflection electron microscopy, F. Heinricht and O. Bostanjoglo 54 (1992) 244

Laser desorption on Si surfaces by use of multiple excimer laser pulses, H. Schlemm, F. Buchmann and H.-D. Geiler 54 (1992) 298

Comparison of laser and line-electron beam recrystallization of thin polycrystalline silicon films, M. Pauli, G. Dähn and J. Müller 54 (1992) 386

Influence of hydrogen on the structure and surface morphology of pulsed ArF excimer laser crystallized amorphous silicon thin films, E.L. Mathé, A. Naudon, M. Elliq, E. Fogarassy and S. de Unamuno 54 (1992) 392

VUV excimer light source for deposition of amorphous semiconductors, F. Kessler and G.H. Bauer 54 (1992) 430

Low temperature photo-assisted oxidation of silicon, A. Kazor and I.W. Boyd 54 (1992) 460

Photoinduced transient reflectance investigation of process-induced near-surface defects in silicon, A. Esser, G. Maidorn and H. Kurz 54 (1992) 482

Sensitivity of a modulated optical reflectance probe to process-induced lattice disorder, M. Murtagh, G.M. Crean, T. Flaherty and C. Jeynes 54 (1992) 497

Grazing incidence X-ray diffraction on silicon after ion implantation and thermal annealing, S. Rugel, H. Metzger, G. Wallner and J. Peisl 54 (1992) 507

Silicon nitride

Deposition of SiON by ArF laser CVD, A. Löffler-Peters, J. Müller and T. Ebert 54 (1992) 121

Rapid thermal chemical vapour deposition of SiO_xN_y films, F. Lebland, C. Licoppe, Y. Gao, Y.I. Nissim and S. Rigo 54 (1992) 125

Silicon oxide

Laser-induced chemical vapour deposition of conductive and insulating thin films, G. Reisse, F. Gaensicke, R. Ebert, U. Illmann and H. Johansen 54 (1992) 84

Control of the $GaAs/SiO_2$ interface through sulfur passivation and a photo-CVD process, Y. Fujisaki 54 (1992) 95

ArF laser induced CVD of SiO_2 films: a search for the best suitable precursors, D. Rieger and F. Bachmann 54 (1992) 99

Excimer laser CVD of silicon oxide on GaAs: a comparison with deposition

on c-Si, P. González, E. García, J. Pou, D. Fernández, B. León and M. Pérez-Amor 54 (1992) 108
Low-temperature silicon oxide films deposited using a CO_2 laser, D. Fernández, P. González, J. Pou, B. León and M. Pérez-Amor 54 (1992) 112
Deposition of SiON by ArF laser CVD, A. Löffler-Peters, J. Müller and T. Ebert 54 (1992) 121
Rapid thermal chemical vapour deposition of SiO_xN_y films, F. Lebland, C. Licoppe, Y. Gao, Y.I. Nissim and S. Rigo 54 (1992) 125
Synthesis of SiO_2 thin films by reactive excimer laser ablation, E. Fogarassy, A. Slaoui, C. Fuchs and J.P. Stoquert 54 (1992) 180
UV annealing of low temperature photodeposited SiO_2 films with a new powerful lamp source, C. Debauche, C. Licoppe, C. Meriadec, F. Sartoris and J. Flicstein 54 (1992) 435
Surface mechanisms in the UVCVD of SiO_2 films, C. Licoppe, C. Meriadec, Y.I. Nissim and J.M. Moison 54 (1992) 445
Improvement of the SiO_2 deposition by 185 nm photolysis of N_2O and SiH_4 by addition of neopentane, M. Petitjean, N. Proust, J.-F. Chapeaublanc and J. Perrin 54 (1992) 453
Low temperature photo-assisted oxidation of silicon, A. Kazor and I.W. Boyd 54 (1992) 460

Silver

Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171

Sputter deposition

Laser deposition of copper oxide thin films: contrast with sputtering, C. Ortiz, C.N. Afonso, F. Vega, J. Solis, J.C. Cheang, C. Ortega and J. Siejka 54 (1992) 201

Sulphur

Control of the $GaAs/SiO_2$ interface through sulfur passivation and a photo-CVD process, Y. Fujisaki 54 (1992) 95

Superconductivity

Study of laser ablation of BiSrCaCuO, R. Pérez Casero, F. Kerhervé, J.P. Enard, J. Perrière and P. Regnier 54 (1992) 147
Laser ablation deposition of PbO/Bi-PbSrCaCuO, A. Sajjadi, M.K. Yau, F. Saba, F. Beech and I.W. Boyd 54 (1992) 154
Ablation studies of Y–Ba–Cu–oxide in oxygen using a pulsed CO_2 laser, P.E. Dyer, P.H. Key and P. Monk 54 (1992) 160
In-situ and multilayer laser ablation deposition of $Pb_2Sr_2Y_{0.5}Ca_{0.5}Cu_3O_{8+\delta}$ thin films, S.H.H. Naqvi, F. Beech and I.W. Boyd 54 (1992) 166
Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171
Fast time-response photoacoustic studies and modelling of KrF laser ablated $YBa_2Cu_3O_7$, P.E. Dyer, S.R. Farrar and P.H. Key 54 (1992) 255
Analysis of the plasma expansion dynamics by optical time-of-flight measurements, W. Marine, M. Gerri, J.M. Scotto d'Aniello, M. Sentis, Ph. Delaporte, B. Forestier and B. Fontaine 54 (1992) 264

Superlattices

Investigation of a semiconductor superlattice by use of grazing incidence X-ray diffraction, U. Pietsch, W. Seifert, J.-O. Fornell, H. Rhan, H. Metzger, S. Rugel and J. Peisl 54 (1992) 502

Surface defects

Photoinduced transient reflectance investigation of process-induced near-surface defects in silicon, A. Esser, G. Maidorn and H. Kurz 54 (1992) 482

Surface structure

Laser–surface diagnostics of GaAs growth processes. II. Reflectance anisotropy studies of GaAs growth by MBE, S.R. Armstrong, M.E. Pemble, A.G. Taylor, B.A. Joyce, J.H. Neave, J. Zhang and D.A. Klug 54 (1992) 493

Tellurium

Production and reactivity of ionic clusters, A. Giardini-Guidoni, G. Pizzella, R. Teghil, M. Foresti, M. Snels and S. Piccirillo 54 (1992) 171

Intriguing properties of pulsed laser beam mixed Au/Te/Au/GaAs ohmic contacts, K. Wuyts, J. Watté and R.E. Silverans 54 (1992) 366

Titanium

Modeling KrF excimer laser induced deposition of titanium from titanium tetrachloride, M. Meunier, C. Lavoie, S. Boivin, R. Izquierdo and P. Desjardins 54 (1992) 52

Reactive TiN deposition on alloys with laser radiation, E.W. Kreutz, M. Krösche, H. Sung, A. Voss and K. Wissenbach 54 (1992) 69

Reactive pulsed laser deposition of TiN, D. Craciun and V. Craciun 54 (1992) 75

IR-laser CVD of TiB_2, TiC_x and TiC_xN_y coatings on carbon fibres, V. Hopfe, A. Tehel, A. Baier and J. Scharsig 54 (1992) 78

CO_2 laser induced CVD of TiN, O. Conde, M.L.G. Ferreira, P. Hochholdinger, A.J. Silvestre and R. Vilar 54 (1992) 130

Laser-induced chemical vapor deposition of titanium diboride, J. Elders and J.D.W. van Voorst 54 (1992) 135

Potential of photon and particle beams for surface treatment of thin ceramic coatings, J.P. Celis, M. Franck, J.R. Roos, E.W. Kreutz, A. Gasser, M. Wehner, K. Wissenbach and N. Pattyn 54 (1992) 322

Multilayer titanium nitride and silicide structures synthesized by multipulse excimer laser irradiation, E. D'Anna, G. Leggieri, A. Luches, M. Martino, A. Perrone, P. Mengucci and I.N. Mihailescu 54 (1992) 353

Laser self-aligned synthesis of $TiSi_2$, V. Craciun, D. Craciun, N. Chitica, I.N. Mihailescu and M. Bertolotti 54 (1992) 362

Laser boronizing of some titanium alloys, C. Badini, M. Bianco, S. Talentino, X.B. Guo and C. Gianoglio 54 (1992) 374

Laser in-diffusion of Ti in $LiNbO_3$ single crystals, M. Bertolotti, V. Craciun, G. De Cesare, A. Ferrari, A. Jascow, I.N. Mihailescu, G. Mikhailova, A. Cino and M. Rossi 54 (1992) 401

Titanium carbide

IR-laser CVD of TiB_2, TiC_x and TiC_xN_y coatings on carbon fibres, V. Hopfe, A. Tehel, A. Baier and J. Scharsig 54 (1992) 78

Direct carbidation of titanium as a result of multipulse UV-laser irradiation of titanium samples in an ambient methane gas, C. Boulmer-Leborgne, J. Hermann, B. Dubreuil, P. Brault, M.L. DeGiorgi, G. Leggieri, A. Luches, M. Martino, A. Perrone, I.N. Mihailescu, I. Ursu, G. Blondiaux, J.L. Debrun, H. Estrade and B. Rousseau 54 (1992) 349

Tribology

Laser-induced structural phase changes in i-carbon films, S. Weissmantel, G. Reisse and S. Schulze 54 (1992) 317

Potential of photon and particle beams for surface treatment of thin ceramic coatings, J.P. Celis, M. Franck, J.R. Roos, E.W. Kreutz, A. Gasser, M. Wehner, K. Wissenbach and N. Pattyn 54 (1992) 322

Laser boronizing of some titanium alloys, C. Badini, M. Bianco, S. Talentino, X.B. Guo and C. Gianoglio 54 (1992) 374

Tungsten

Spectroscopic investigations of gas-phase chemistry during laser-induced photolytic CVD of W, P. Mogyorósi, J.O. Carlsson and M. Moradi 54 (1992) 46

Laser-induced damage formation and tungsten deposition on GaAs, A. Lecours, M. Meunier and R. Izquierdo 54 (1992) 60

Laser-induced chemical vapour deposition of conductive and insulating thin films, G. Reisse, F. Gaensicke, R. Ebert, U. Illmann and H. Johansen 54 (1992) 84

Kinetics of excimer-laser induced CVD of W, R.L. Krans, C. Brands and W.C. Sinke 54 (1992) 117

Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215

Tunneling

Fabrication of nanometer structures using STM, R. Wiesendanger 54 (1992) 271

X-ray diffraction

Laser ablation deposition of PbO/Bi-PbSrCaCuO, A. Sajjadi, M.K. Yau, F. Saba, F. Beech and I.W. Boyd 54 (1992) 154
In-situ and multilayer laser ablation deposition of $Pb_2Sr_2Y_{0.5}Ca_{0.5}Cu_3O_{8+\delta}$ thin films, S.H.H. Naqvi, F. Beech and I.W. Boyd 54 (1992) 166
Thin film deposition of dielectric oxides by laser ablation, S. Amirhaghi, A. Archer, B. Taguiang, R. McMinn, P. Barnes, S. Tarling and I.W. Boyd 54 (1992) 205
Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215
Laser boronizing of some titanium alloys, C. Badini, M. Bianco, S. Talentino, X.B. Guo and C. Gianoglio 54 (1992) 374
Influence of hydrogen on the structure and surface morphology of pulsed ArF excimer laser crystallized amorphous silicon thin films, E.L. Mathé, A. Naudon, M. Elliq, E. Fogarassy and S. de Unamuno 54 (1992) 392
Investigation of a semiconductor superlattice by use of grazing incidence X-ray diffraction, U. Pietsch, W. Seifert, J.-O. Fornell, H. Rhan, H. Metzger, S. Rugel and J. Peisl 54 (1992) 502
Grazing incidence X-ray diffraction on silicon after ion implantation and thermal annealing, S. Rugel, H. Metzger, G. Wallner and J. Peisl 54 (1992) 507

X-ray emission

Reactive pulsed laser deposition of TiN, D. Craciun and V. Craciun 54 (1992) 75
Laser self-aligned synthesis of $TiSi_2$, V. Craciun, D. Craciun, N. Chitica, I.N. Mihailescu and M. Bertolotti 54 (1992) 362

X-ray scattering

Manufacture and characterization of soft X-ray mirrors by laser ablation, H. Mai and W. Pompe 54 (1992) 215

Zinc

Influence of laser assistance on the nucleation and growth processes occurring during the electrodeposition of zinc, I. Zouari, M. Calvo, F. Lapicque and M. Cabrera 54 (1992) 311